

FIG. 1

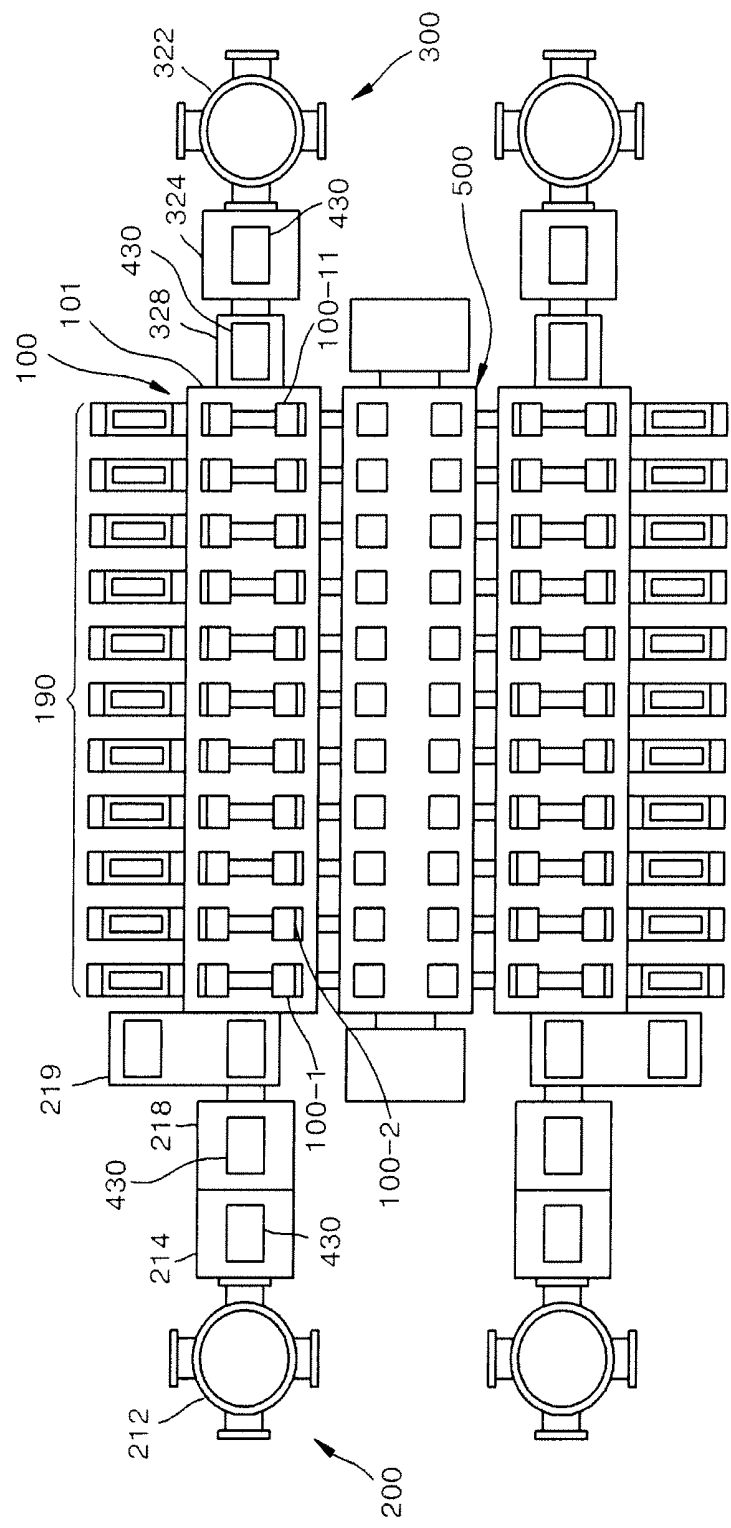


FIG. 2

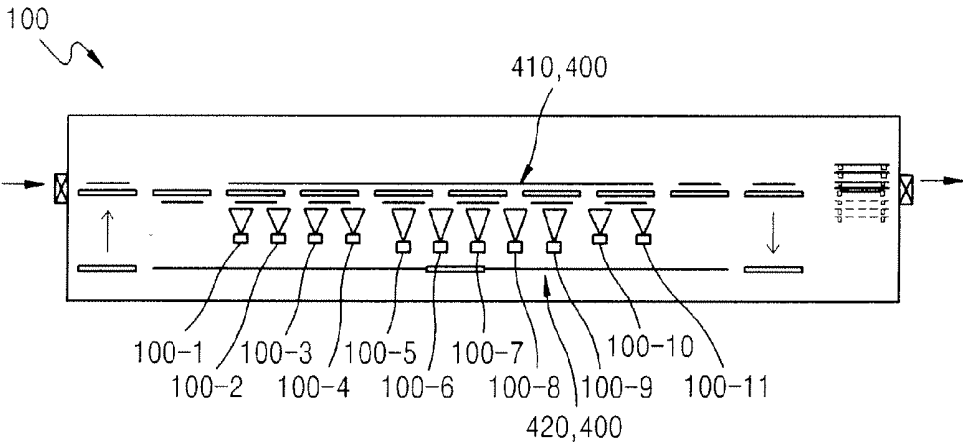
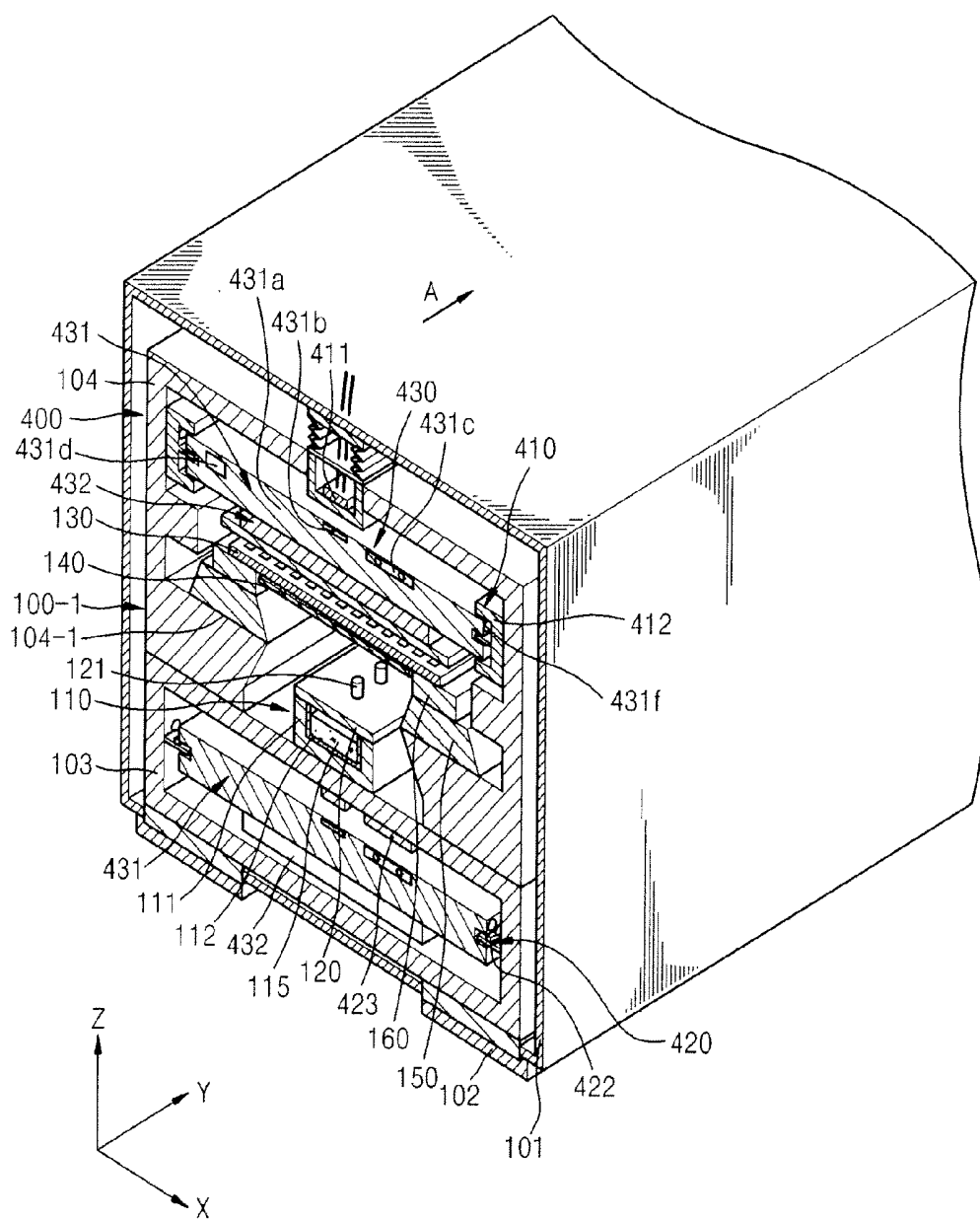


FIG. 3



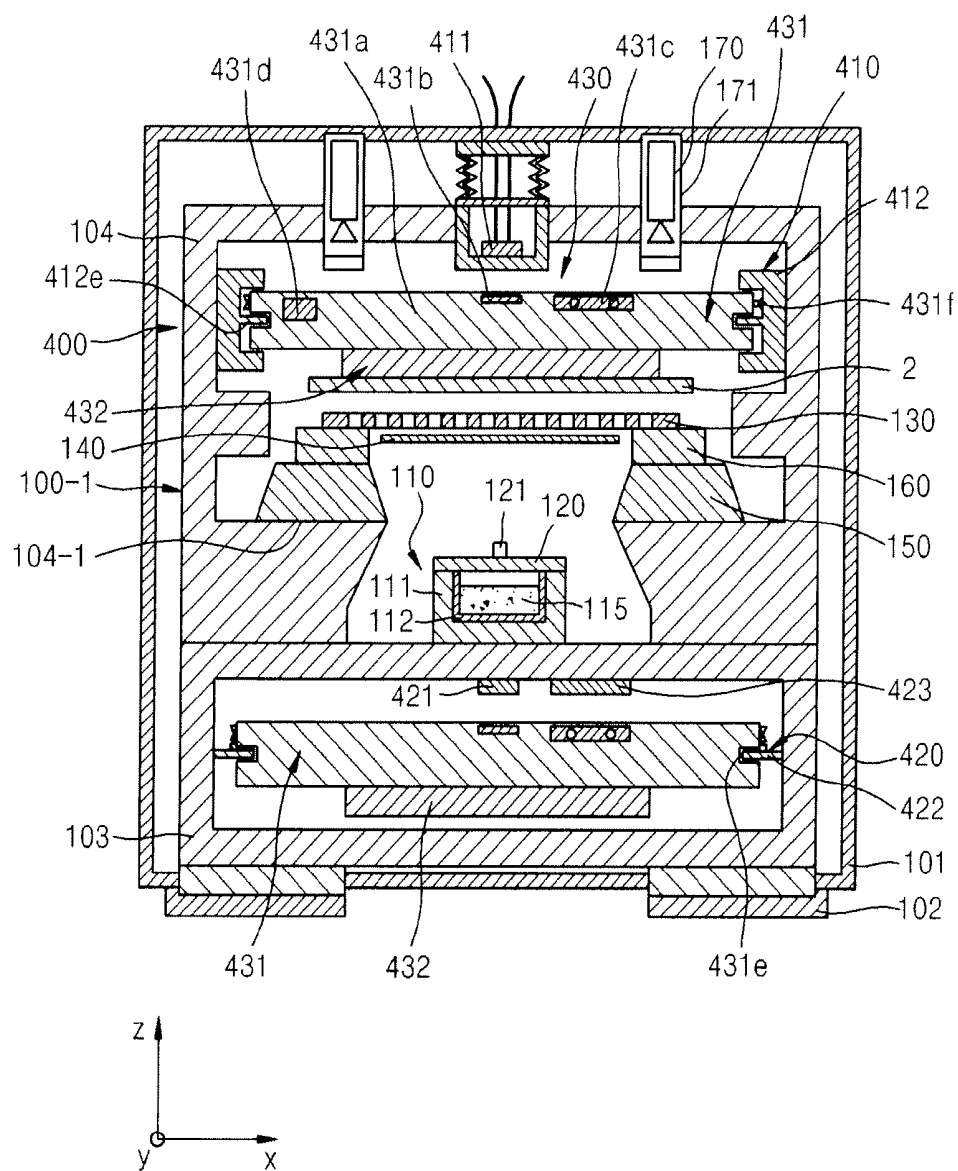


FIG. 5

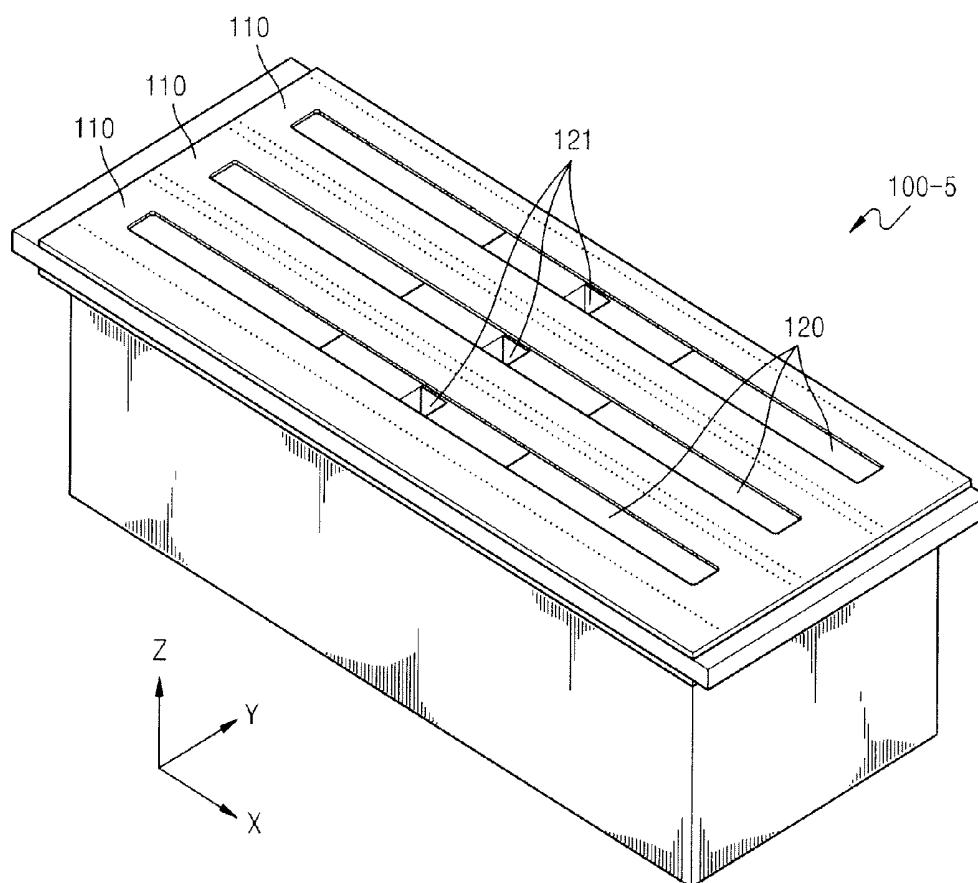


FIG. 6

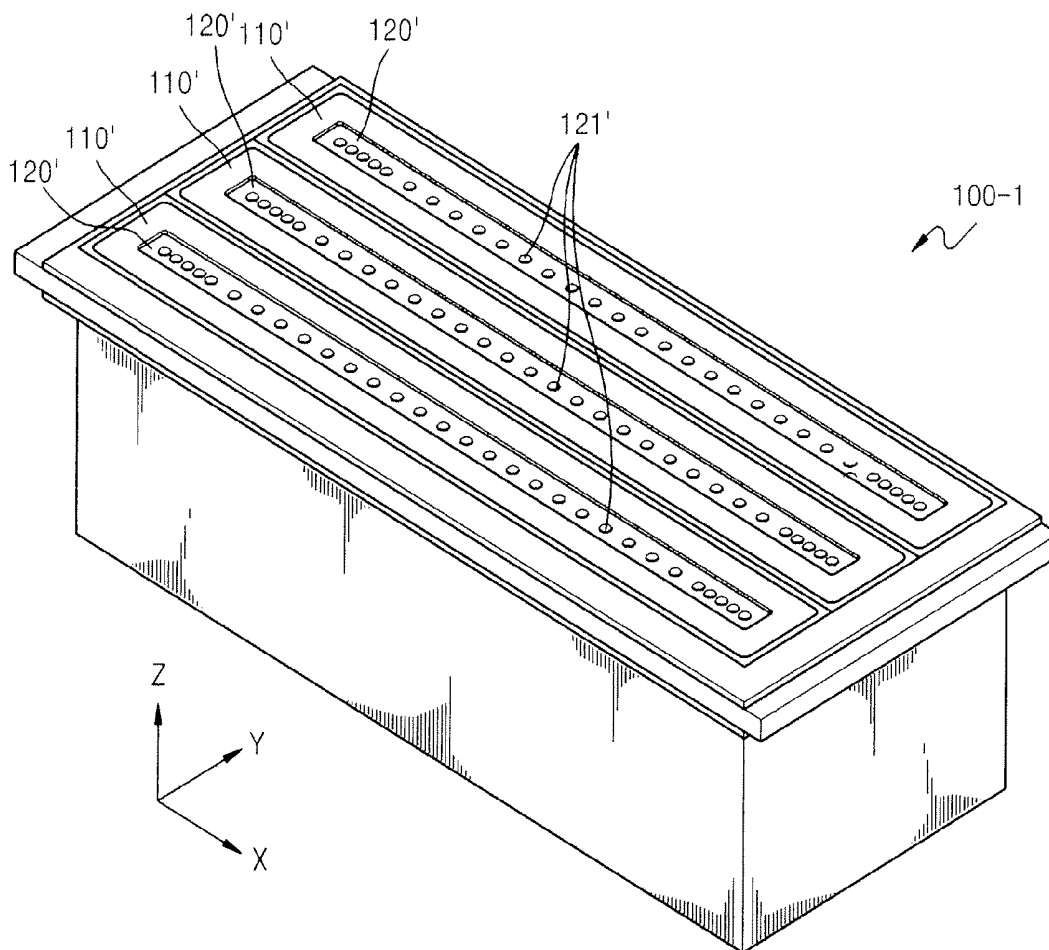


FIG. 7

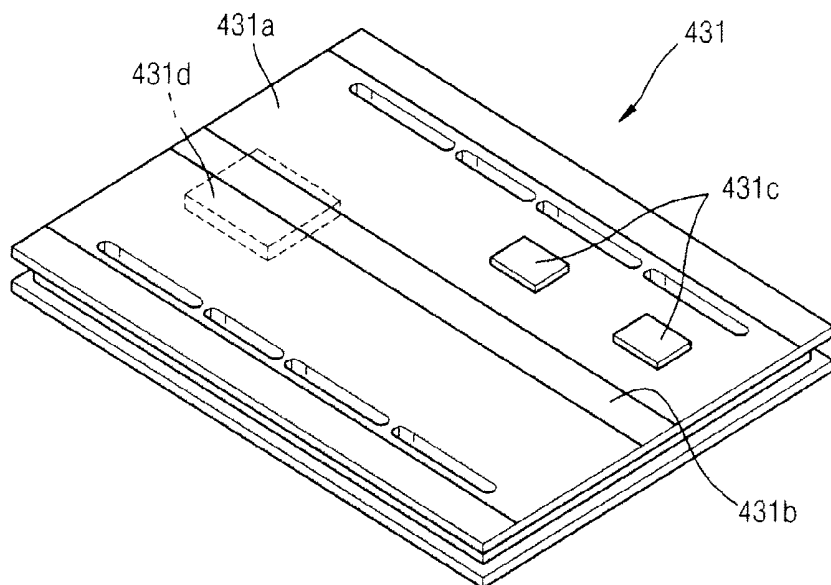


FIG. 8

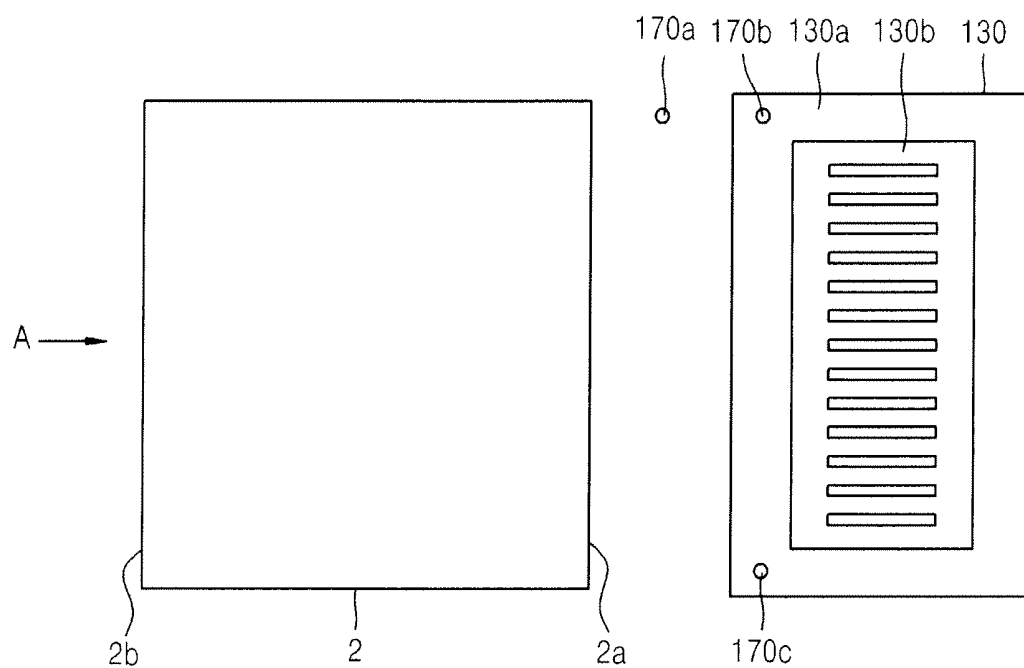


FIG. 9

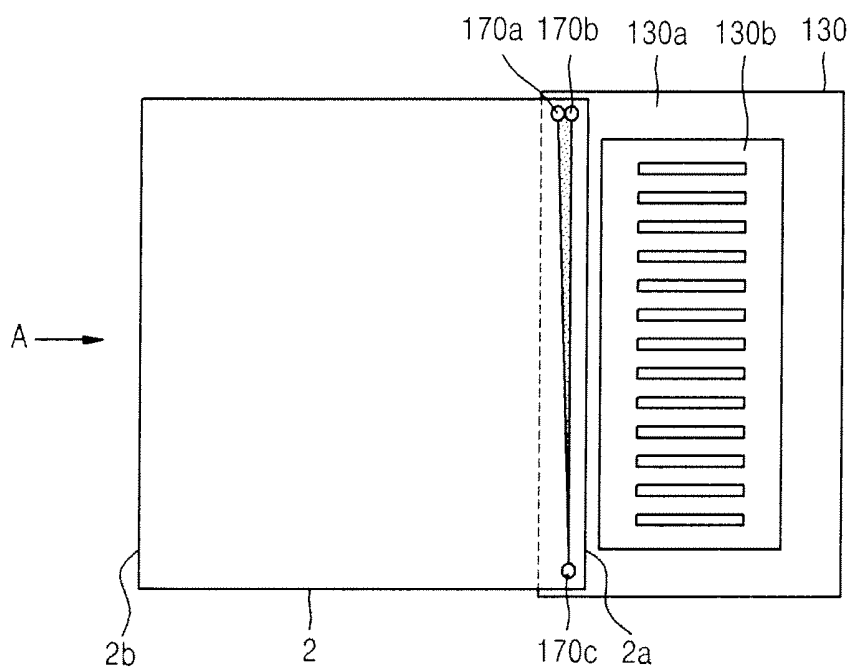


FIG. 10

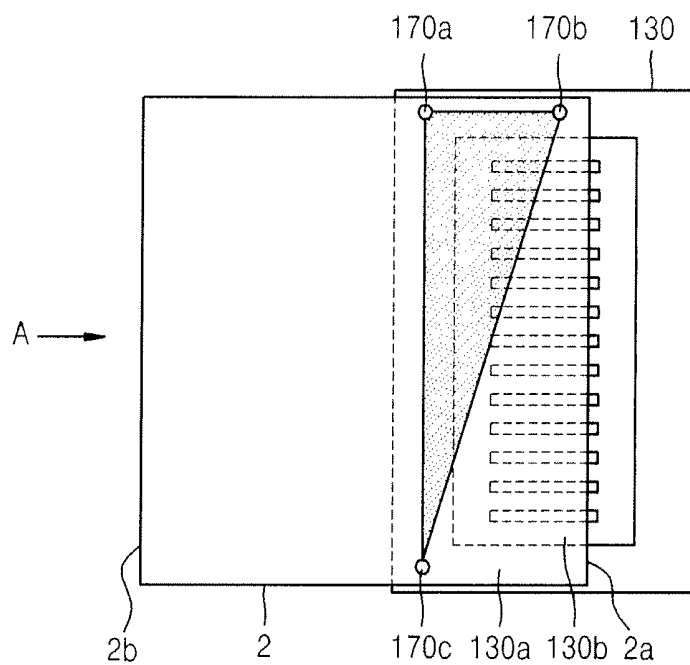
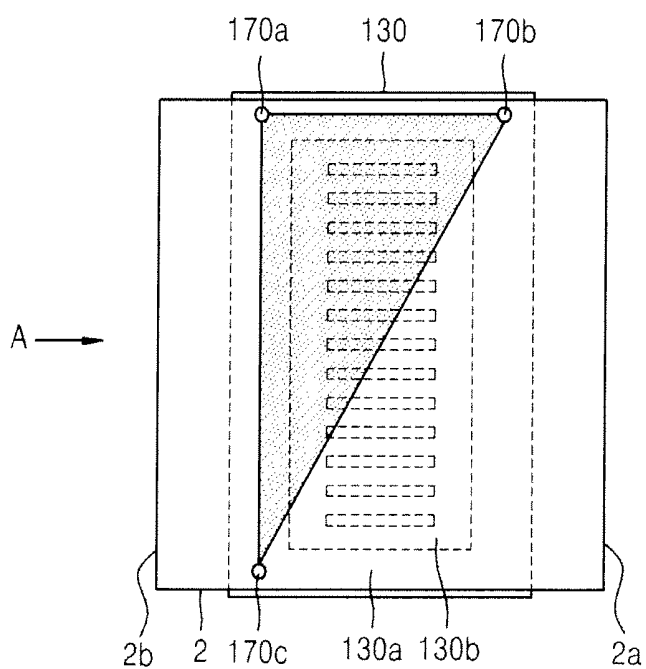


FIG. 11



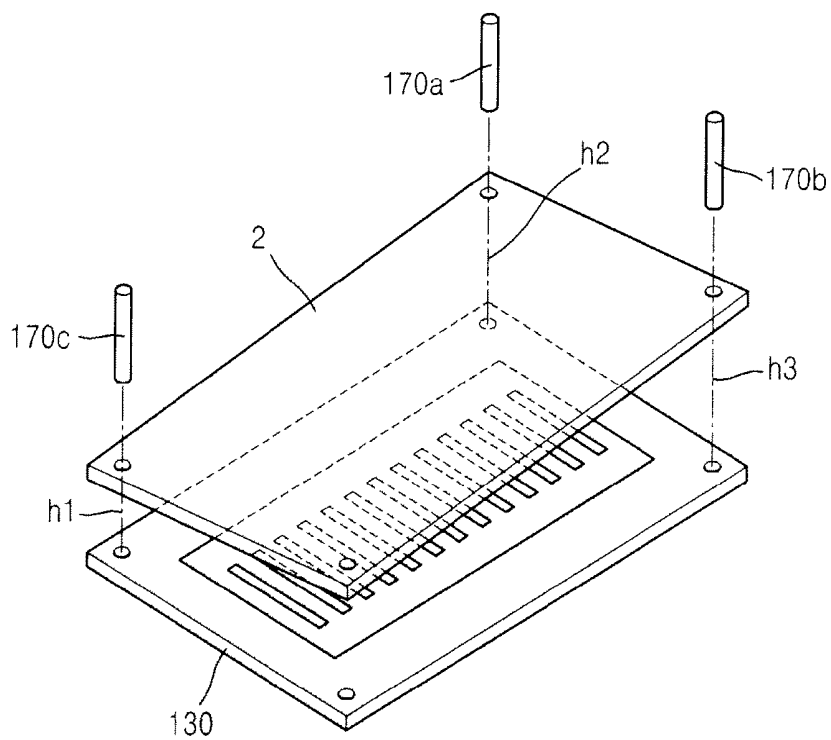


FIG. 14

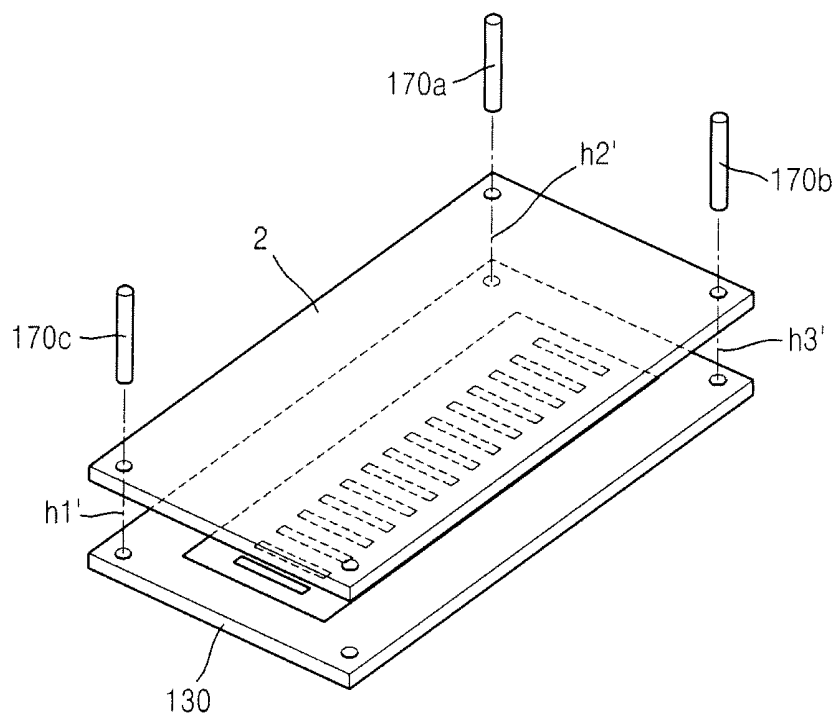


FIG. 15

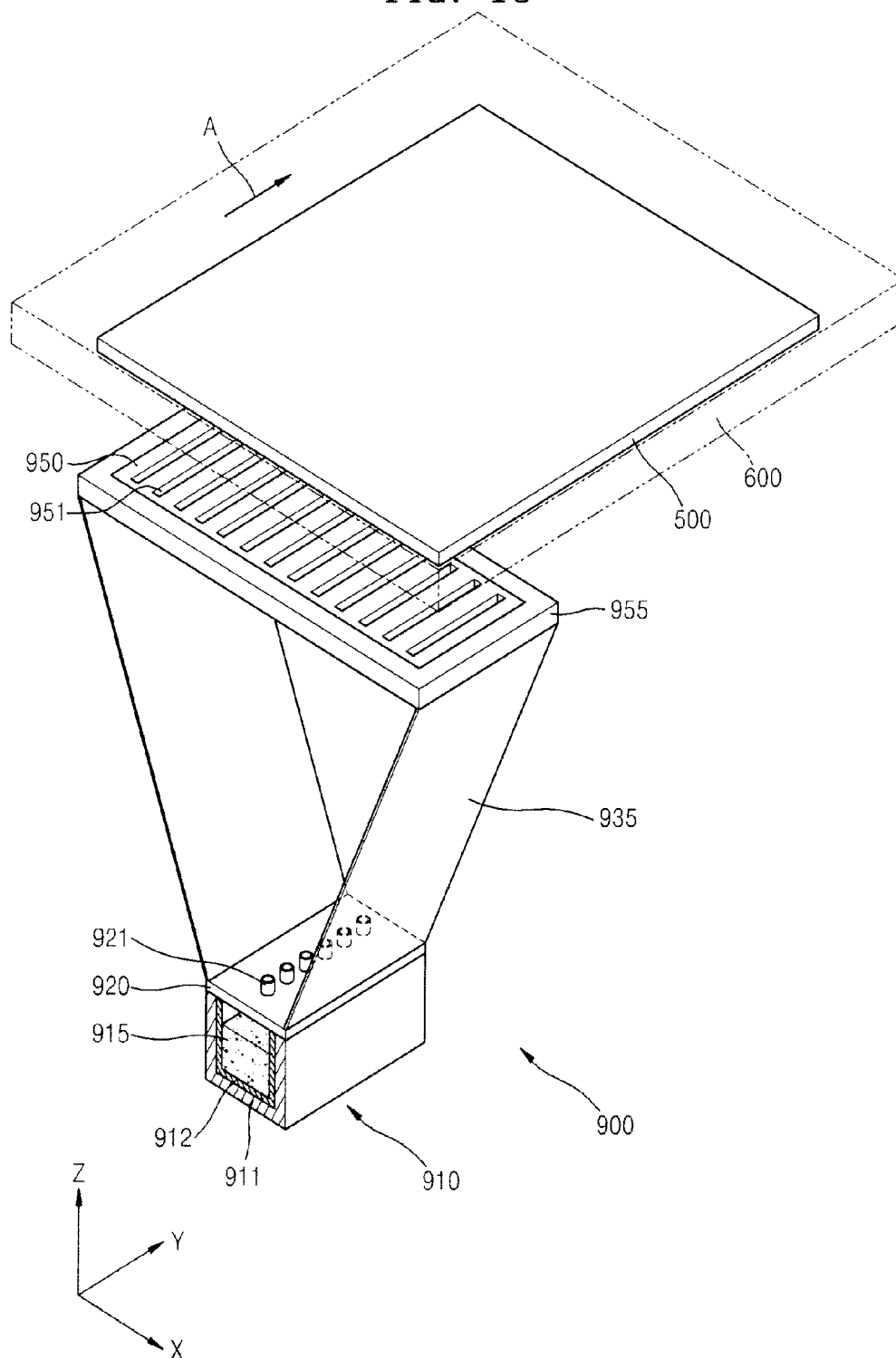


FIG. 16

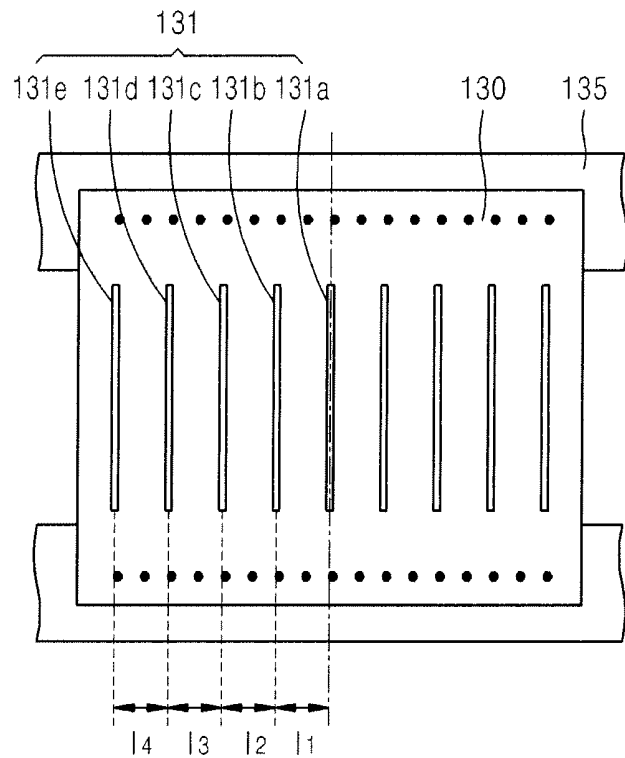


FIG. 17

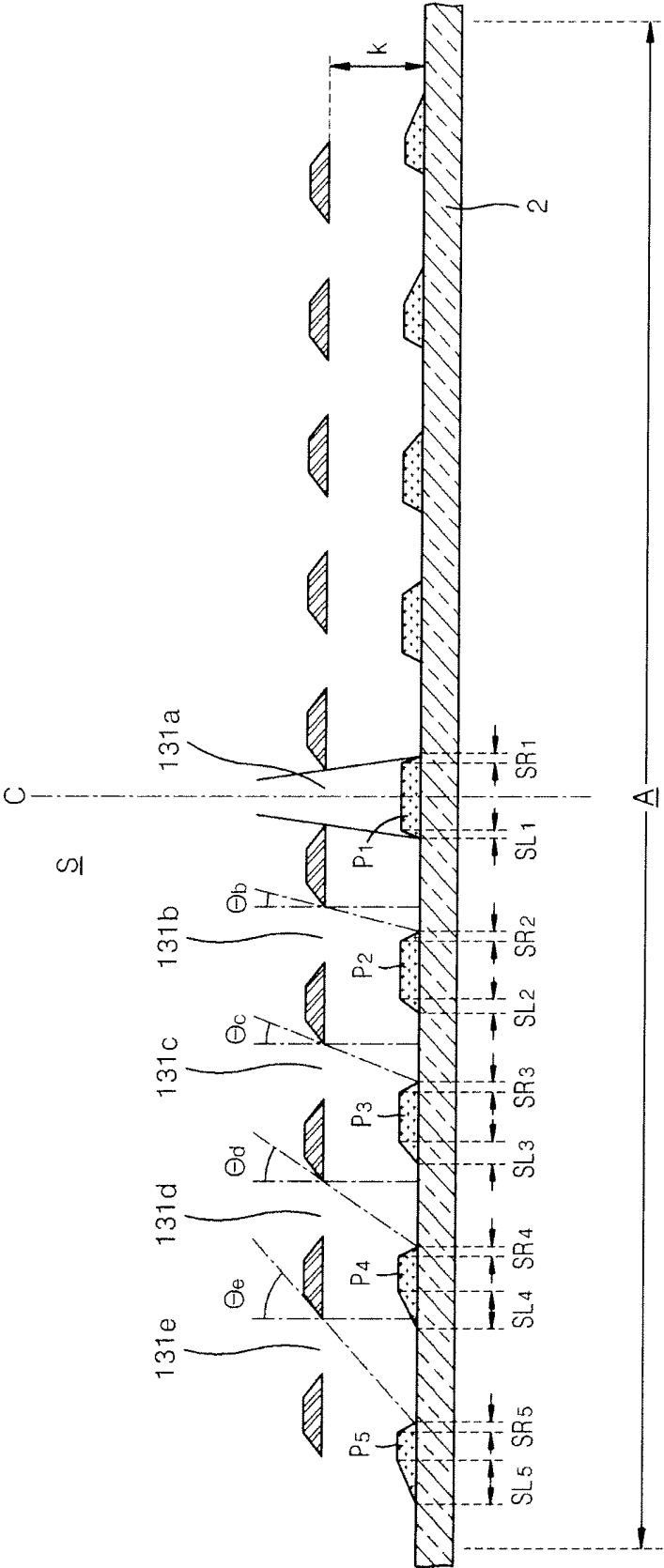
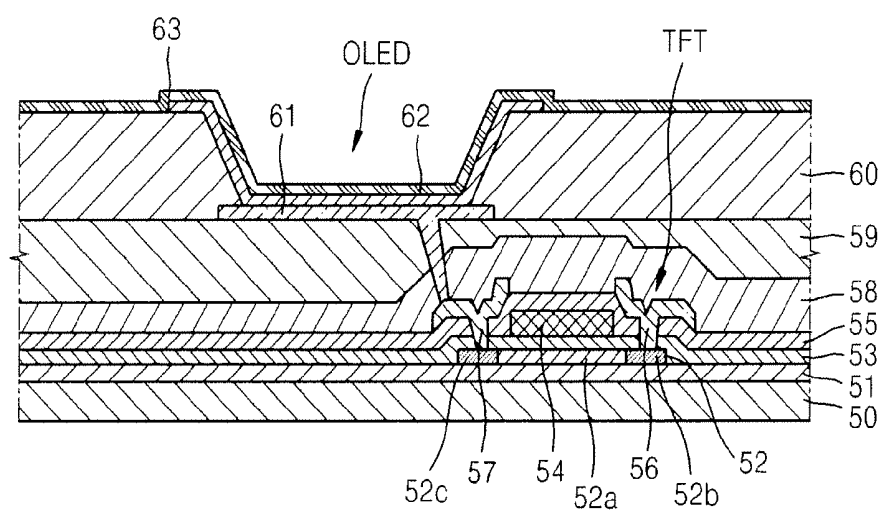


FIG. 18



**METHOD OF MANUFACTURING ORGANIC
LIGHT-EMITTING DISPLAY APPARATUS,
AND ORGANIC LIGHT-EMITTING DISPLAY
APPARATUS MANUFACTURED BY THE
METHOD**

**CROSS-REFERENCE TO RELATED PATENT
APPLICATION**

[0001] This application claims priority to and the benefit of Korean Patent Application No. 10-2013-0029910, filed on Mar. 20, 2013, in the Korean Intellectual Property Office, the entire content of which is incorporated herein by reference.

BACKGROUND

[0002] 1. Field

[0003] Aspects of the present invention relate to a method of manufacturing an organic light-emitting display apparatus, and an organic light-emitting display apparatus manufactured by the method.

[0004] 2. Description of the Related Art

[0005] Organic light-emitting display apparatuses have wider viewing angles, better contrast characteristics, and faster response speeds than other display apparatuses, and thus, have drawn attention as the next-generation of display apparatuses.

[0006] An organic light-emitting display apparatus includes intermediate layers (including an emission layer) disposed between a first electrode and a second electrode. The electrodes and the intermediate layers may be formed using various methods such as a deposition method using a fine metal mask (FMM). In this case, a FMM having the same pattern as that of a deposition layer to be formed is disposed to closely contact a substrate on which the deposition layer is to be formed, and a deposition material is deposited on the FMM to form the deposition layer having the desired pattern.

[0007] However, the deposition method using such an FMM presents difficulties in manufacturing larger organic light-emitting display apparatuses that use a large mother glass (substrate). For example, when such a large mask is used with the large mother glass, the mask may bend due to gravity, thereby distorting a pattern of a deposition layer. Such disadvantages are not conducive to the recent trend for forming high-definition patterns.

[0008] Moreover, processes of aligning a substrate and an FMM to closely contact each other, performing deposition thereon, and separating the FMM from the substrate are time-consuming, thereby resulting in a long manufacturing time and low yield.

SUMMARY

[0009] According to aspects of the present invention, methods of manufacturing organic light emitting display apparatuses are suitable for mass producing large substrates, enabling high-definition patterning, and allowing control of distances between a patterning slit sheet and a substrate which are moving relative to each other, and organic light-emitting display apparatuses manufactured by the methods.

[0010] According to an embodiment of the present invention, a method of manufacturing an organic light emitting display apparatus includes: fixing a substrate to a transfer unit at a loading unit; transporting the transfer unit on which the substrate is fixed in a first direction into a chamber by using a first conveyer unit that passes through the chamber; deposit-

ing a deposition material that is emitted from a deposition assembly by relatively moving the substrate with respect to the deposition assembly, while the deposition assembly disposed in the chamber and the substrate are separated from each other in a distance; separating the substrate on which deposition is completed from the transfer unit at an unloading unit; and transporting the transfer unit that is separated from the substrate to the loading unit by using a second conveyer unit, wherein the depositing of the deposition material includes measuring an interval between the substrate and the deposition assembly while the substrate relatively moves with respect to the deposition assembly.

[0011] Additional deposition assemblies may be disposed in the chamber so as to perform deposition on the substrate consecutively.

[0012] The transfer unit may be circulated by the first conveyer unit and the second conveyer unit.

[0013] One of the first conveyer unit and the second conveyer unit may be disposed on top of the other.

[0014] A patterning slit sheet of the deposition assembly may be smaller than the substrate in at least one of the first direction and a second direction perpendicular to the first direction.

[0015] The deposition assembly may include: a deposition source configured to discharge the deposition material; a deposition source nozzle unit installed at a side of the deposition source and including a plurality of deposition source nozzles; a patterning slit sheet facing the deposition source nozzle unit and including a plurality of patterning slits formed along a direction; and an interval measuring assembly configured to move relatively with respect to a substrate and the patterning slit sheet in order to measure an interval between the substrate and the patterning slit sheet, wherein the patterning slit sheet includes a patterning unit having a plurality of patterning slits and a non-patterning unit that surrounds the patterning unit and has no patterning slit, and wherein the interval measuring assembly includes at least three interval measuring units, and positions where the at least three interval measuring units are disposed are located on a single virtual plane, and the points at which the interval measuring units are disposed are not arranged along a straight line.

[0016] The at least three interval measuring units may include a first interval measuring unit, a second interval measuring unit, and a third interval measuring unit, wherein virtual lines that connect the locations where the first interval measuring unit, the second interval measuring unit, and the third interval measuring unit are located form a triangle, and while the first interval measuring unit, the second interval measuring unit, and the third interval measuring unit move in a first direction or in a third direction opposite the first direction, the virtual lines that connect the locations where the first interval measuring unit, the second interval measuring unit, and the third interval measuring unit are disposed form a triangle.

[0017] The measuring of the interval may include, when the substrate is transported in the first direction such that a side portion of the substrate is located on the non-patterning unit: measuring a distance with respect to the substrate and a distance with respect to the patterning slit sheet while the first interval measuring unit, the second interval measuring unit, and the third interval measuring unit are located above a portion of the substrate corresponding to the non-patterning unit, so as to calculate intervals between the substrate and the patterning slit sheet at each of the locations where the first

interval measuring unit, the second interval measuring unit, and the third interval measuring unit are located; and when there is a difference in the intervals between the patterning slit sheet and the substrate at each of the positions where the first interval measuring unit, the second interval measuring unit, and the third interval measuring unit are located, moving the patterning slit sheet such that the intervals become identical.

[0018] The measuring of the interval may include, when the substrate is transported in the first direction so that the side portion of the substrate passes above the patterning unit: calculating an interval between the substrate and the patterning slit sheet by using the second interval measuring unit moving at the same speed as a transportation speed of the substrate in the first direction to measure distances of the second interval measuring unit with respect to the substrate and the patterning slit sheet; and when there is a difference in intervals between the substrate and the patterning slit sheet at each of the positions where the first interval measuring unit, the second interval measuring unit, and the third interval measuring unit are located, moving the patterning slit sheet such that the intervals become identical.

[0019] The first interval measuring unit and the third interval measuring unit may be stationary above the non-patterning unit to measure respective distances of the first interval measuring unit and the third interval measuring unit with respect to the substrate and the patterning slit sheet to calculate intervals between the substrate and the patterning slit sheet.

[0020] The measuring of an interval may include, when the substrate is transported in the first direction so that the side portion of the substrate passes above the patterning unit and the non-patterning unit to be out of the non-patterning unit: calculating intervals between the substrate and the patterning slit sheet by measuring respective distances of the first, second, and third interval measuring units with respect to the substrate and the patterning slit sheet, the second interval unit being stationary above a portion of the non-patterning unit adjacent to a first side portion of the substrate with respect to the patterning unit, and the first interval measuring unit and the third interval measuring unit being stationary above portions of the non-patterning unit adjacent to a second side portion of the substrate with respect to the patterning unit; and when there is a difference in intervals between the substrate and the patterning slit sheet at each of the portions where the first interval measuring unit, the second interval measuring unit, and the third interval measuring unit are located, moving the patterning slit sheet such that the intervals become identical.

[0021] The measuring of an interval may include, when the substrate is transported in the first direction so that a portion of the patterning slit sheet does not correspond to the substrate: calculating intervals between the substrate and the patterning slit sheet by measuring respective distances of the first, second, and third interval measuring units with respect to the substrate and the patterning slit sheet, the second interval unit being stationary above a portion of the non-patterning unit adjacent to a first side portion of the substrate with respect to the patterning unit, and the first interval measuring unit and the third interval measuring unit moving in the first direction as the same speed as a transportation speed of the substrate; and when there is a difference in intervals between the substrate and the patterning slit sheet at each of the portions where the first interval measuring unit, the second interval

measuring unit, and the third interval measuring unit are located, moving the patterning slit sheet such that the intervals become identical.

[0022] According to another embodiment of the present invention, an organic light-emitting display apparatus includes: a substrate; a thin film transistor disposed on the substrate and including a semiconductor active layer, a gate electrode insulated from the semiconductor active layer, and source and drain electrodes each contacting the semiconductor active layer; a plurality of pixel electrodes disposed on the thin film transistor; a plurality of deposition layers disposed on the plurality of the pixel electrodes; and a counter electrode formed on the plurality of deposition layers, wherein a length of a hypotenuse of at least one of the plurality of deposition layers on the substrate farther from a center of a deposition region is larger than lengths of hypotenuses of other deposition layers formed closer to the center of the deposition region, and wherein the at least one of the plurality of deposition layers on the substrate is a linearly-patterned deposition layer formed by using the method described above.

BRIEF DESCRIPTION OF THE DRAWINGS

[0023] The above and other features and advantages of the present invention will become more apparent by describing in more detail some example embodiments thereof with reference to the attached drawings in which:

[0024] FIG. 1 is a schematic plan view illustrating a structure of a deposition apparatus according to an embodiment of the present invention;

[0025] FIG. 2 is a schematic side view of a deposition unit of the deposition apparatus of FIG. 1, according to an embodiment of the present invention;

[0026] FIG. 3 is a schematic perspective view of the deposition unit of the deposition apparatus of FIG. 1, according to an embodiment of the present invention;

[0027] FIG. 4 is a schematic cross-sectional view of the deposition unit of FIG. 3, according to an embodiment of the present invention;

[0028] FIG. 5 is a perspective view of a deposition source of the deposition unit of FIG. 3, according to an embodiment of the present invention;

[0029] FIG. 6 is a perspective view of a deposition source of the deposition unit of FIG. 3, according to another embodiment of the present invention;

[0030] FIG. 7 is a perspective view illustrating a carrier of the deposition unit of FIG. 3, according to an embodiment of the present invention;

[0031] FIG. 8 is a schematic plan view illustrating an interval measuring unit and a patterning slit sheet according to an embodiment of the present invention;

[0032] FIGS. 9 through 12 are schematic plan views illustrating an operation of measuring an interval between a substrate and a patterning slit sheet, by using the interval measuring unit according to an embodiment of the present invention;

[0033] FIGS. 13 and 14 are perspective views illustrating an interval between a substrate and a patterning slit sheet, according to an embodiment of the present invention;

[0034] FIG. 15 illustrates a deposition assembly according to another embodiment of the present invention;

[0035] FIG. 16 is a diagram illustrating a structure in which patterning slits are formed at equal intervals in a patterning

slit sheet of the deposition apparatus including the deposition unit of FIG. 3, according to an embodiment of the present invention;

[0036] FIG. 17 is a diagram illustrating organic layers formed on a substrate by using the patterning slit sheet of FIG. 16, according to an embodiment of the present invention; and [0037] FIG. 18 is a cross-sectional view of an active matrix-type organic light-emitting display apparatus manufactured by using a deposition apparatus, according to an embodiment of the present invention.

DETAILED DESCRIPTION

[0038] Reference will now be made in more detail to some embodiments of the present invention, examples of which are illustrated in the accompanying drawings, wherein like reference numerals refer to the like elements throughout. The embodiments are described below in order to explain aspects of the present invention by referring to the figures. Expressions such as “at least one of,” when preceding a list of elements, modify the entire list of elements and do not modify the individual elements of the list.

[0039] FIG. 1 is a schematic plan view illustrating a structure of a deposition apparatus according to an embodiment of the present invention. FIG. 2 is a schematic side view of a deposition unit 100 of the deposition apparatus of FIG. 1, according to an embodiment of the present invention.

[0040] Referring to FIGS. 1 and 2, the deposition apparatus includes the deposition unit 100, a loading unit 200, an unloading unit 300, and a conveyer unit 400.

[0041] The loading unit 200 may include a first rack 212, a transport chamber 214, a first inversion chamber 218, and a buffer chamber 219.

[0042] A plurality of substrates 2 onto which a deposition material has not yet been deposited are stacked up on the first rack 212. A transport robot included in the transport chamber 214 picks up one of the substrates 2 from the first rack 212, disposes it on a transfer unit 430 transferred by a second conveyer unit 420, and moves the transfer unit 430 on which the substrate 2 is disposed into the first inversion chamber 218.

[0043] The first inversion chamber 218 is disposed adjacent to the transport chamber 214. The first inversion chamber 218 includes a first inversion robot that inverts the transfer unit 430 and then loads it on a first conveyer unit 410 of the deposition unit 100.

[0044] Referring to FIG. 1, the transport robot of the transport chamber 214 places one of the substrates 2 on a top surface of the transfer unit 430, and the transfer unit 430 on which the substrate 2 is disposed is then transferred into the first inversion chamber 218. The first inversion robot of the first inversion chamber 218 inverts the first inversion chamber 218 so that the substrate 2 is turned upside down in the deposition unit 100.

[0045] The unloading unit 300 is configured to operate in an opposite manner to the loading unit 200 described above. Specifically, a second inversion robot in a second inversion chamber 328 inverts the transfer unit 430, which has passed through the deposition unit 100 while the substrate 2 is disposed on the transfer unit 430, and then moves the transfer unit 430 on which the substrate 2 is disposed into an ejection chamber 324. Then, an ejection robot takes the transfer unit 430 on which the substrate 2 is disposed out of the ejection chamber 324, separates the substrate 2 from the transfer unit 430, and then loads the substrate 2 on a second rack 322. The

transfer unit 430, which is separated from the substrate 2, is returned to the loading unit 200 via the second conveyer unit 420.

[0046] However, the present invention is not limited to the above example. For example, when disposing the substrate 2 on the transfer unit 430, the substrate 2 may be fixed onto a bottom surface of the transfer unit 430 and then moved into the deposition unit 100. In such an embodiment, for example, the first inversion robot of the first inversion chamber 218 and the second inversion robot of the second inversion chamber 328 may be omitted.

[0047] The deposition unit 100 may include at least one chamber for deposition. In one embodiment, as illustrated in FIGS. 1 and 2, the deposition unit 100 includes a chamber 101 in which a plurality of deposition assemblies 100-1, 100-2, . . . 100-*n* may be disposed. Referring to FIG. 1, 11 deposition assemblies, i.e., a first deposition assembly 100-1, a second deposition assembly 100-2, and an eleventh deposition assembly 100-11, are disposed in the chamber 101, but the number of deposition assemblies may vary with the deposition material and deposition conditions. The chamber 101 is maintained in vacuum during the deposition process.

[0048] In the embodiment illustrated in FIG. 1, the transfer unit 430 with the substrate 2 fixed thereon may be moved at least to the deposition unit 100 or may be moved sequentially by the first conveyer unit 410 to the loading unit 200, the deposition unit 100, and the unloading unit 300, and the transfer unit 430 that is separated from the substrate 2 in the unloading unit 300 may be moved back to the loading unit 200 by the second conveyer unit 420.

[0049] The first conveyer unit 410 passes through the chamber 101 when passing through the deposition unit 100, and the second conveyer unit 420 conveys the transfer unit 430 from which the substrate 2 is separated.

[0050] In the present embodiment, the deposition apparatus is configured such that one of the first conveyer unit 410 and the second conveyer unit 420 is disposed in upper portion of the other so that after the transfer unit 430, on which deposition has been completed while passing through the first conveyer unit 410, is separated from the substrate 2 in the unloading unit 300, the transfer unit 430 is returned to the loading unit 200 via the second conveyer unit 420 formed above or below the first conveyer unit 410, and accordingly, the deposition apparatus may have an improved space utilization efficiency.

[0051] In an embodiment, the deposition unit 100 of FIG. 1 may further include a deposition source replacement unit 190 disposed at a side of each deposition assembly. Although not particularly illustrated in the drawings, the deposition source replacement unit 190 may be a cassette-type unit that may be taken out completely from each deposition assembly. Thus, a deposition source 110 (refer to FIG. 3) of the deposition assembly 100-1 may be easily replaced.

[0052] FIG. 1 illustrates the deposition apparatus in which two sets of structures each including the loading unit 200, the deposition unit 100, the unloading unit 300, and the conveyer unit 400 are arranged in parallel. That is, it can be seen that two deposition units 100 are respectively arranged at opposite sides of the deposition apparatus in upper and lower portions of FIG. 1. In such an embodiment, a patterning slit sheet replacement unit 500 may be disposed between the two deposition units 100. That is, due to this configuration of structures, the two deposition units 100 share the patterning slit sheet replacement unit 500, which results in improved space

utilization efficiency as compared to a case where each deposition unit **100** includes the patterning slit sheet replacement unit **500**.

[0053] FIG. 3 is a schematic perspective view of the deposition unit **100** of the deposition apparatus of FIG. 1, according to an embodiment of the present invention. FIG. 4 is a schematic cross-sectional view of the deposition unit **100** of FIG. 3, according to an embodiment of the present invention. FIG. 5 is a perspective view of three deposition sources **110** of the deposition unit **100** of FIG. 3, according to an embodiment of the present invention. FIG. 6 is a perspective view of three deposition sources **110'** of the deposition unit **100** of FIG. 3, according to another embodiment of the present invention. FIG. 7 is a perspective view particularly illustrating a carrier **431** of a transfer unit **430** of the deposition unit **100** of FIG. 3, according to an embodiment of the present invention.

[0054] Referring to FIGS. 3 and 4, the deposition unit **100** of the deposition apparatus includes at least one deposition assembly **100-1** and a conveyer unit **400**.

[0055] Hereinafter, an overall structure of the deposition unit **100** will be described.

[0056] The chamber **101** may be of a hollow box type and accommodate the at least one deposition assembly **100-1** and the transfer unit **430**. In another embodiment, a foot **102** is formed so as to fix the deposition unit **100** on the ground, a lower housing **103** is disposed on the foot **102**, and an upper housing **104** is disposed on the lower housing **103**. The chamber **101** accommodates both the lower housing **103** and the upper housing **104**. In this regard, a connection part of the lower housing **103** and the chamber **101** is sealed so that the inside of the chamber **101** is completely isolated from the outside. Due to the structure in which the lower housing **103** and the upper housing **104** are disposed on the foot **102** fixed on the ground, the lower housing **103** and the upper housing **104** may be maintained in a fixed position even though the chamber **101** is repeatedly contracted and expanded. Thus, the lower housing **103** and the upper housing **104** may serve as a reference frame in the deposition unit **100**.

[0057] The upper housing **104** includes the deposition assembly **100-1** and the first conveyer unit **410** of the conveyer unit **400**, and the lower housing **103** includes the second conveyer unit **420** of the conveyer unit **400**. A deposition process is continuously performed while the transfer unit **430** is cyclically moving between the first conveyer unit **410** and the second conveyer unit **420**.

[0058] Hereinafter, elements of the deposition assembly **100-1** are described in more detail.

[0059] The first deposition assembly **100-1** includes the deposition source **110**, a deposition source nozzle unit **120**, a patterning slit sheet **130**, a shielding member **140**, a first stage **150**, a second stage **160**, an interval measuring assembly **170**, or the like. In this regard, all the elements illustrated in FIGS. 3 and 4 may be arranged in the chamber **101** maintained in an appropriate vacuum state. This structure is needed to achieve linearity of a deposition material.

[0060] In particular, in order to deposit a deposition material **115**, which has been discharged from the deposition source **110** and passed through the deposition source nozzle unit **120** and the patterning slit sheet **130**, onto the substrate **2** in a desired pattern, it is desirable to maintain the chamber in the same vacuum state as that used in a deposition method of an FMM. In addition, the temperature of the patterning slit sheet **130** should be sufficiently lower than that of the depo-

sition source **110** because thermal expansion of the patterning slit sheet **130** is reduced or minimized when the temperature of the patterning slit sheet **130** is sufficiently low.

[0061] The substrate **2** on which the deposition material **115** is to be deposited is arranged in the chamber **101**. The substrate **2** may be a substrate for a flat panel display apparatus. For example, a large substrate of 40 inches or larger, such as a mother glass, for manufacturing a plurality of flat panel displays, may be used as the substrate **2**.

[0062] According to an embodiment, the deposition process may be performed by moving the substrate **2** relative to the deposition assembly **100-1**.

[0063] In a comparable deposition method using an FMM, the size of the FMM needs to be the same as that of a substrate. Thus, as the size of the substrate increases, the FMM also needs to be large in size. Due to these problems, it is difficult to fabricate the FMM and to align the FMM in a precise pattern by elongating the FMM.

[0064] To address these problems, in the deposition assembly **100-1** according to the present embodiment, deposition may be performed while one of the deposition assembly **100-1** and the substrate **2** moves relative to the other. In one embodiment, deposition may be continuously performed while the substrate **2**, which faces the deposition assembly **100-1**, moves in the Y-axis direction. That is, deposition is performed in a scanning manner while the substrate **2** moves in a direction of arrow A illustrated in FIG. 3. Although the substrate **2** is illustrated as moving in the Y-axis direction in the chamber **101** in FIG. 3 when deposition is performed, the present invention is not limited thereto. For example, deposition may be performed while the deposition assembly **100-1** moves in the Y-axis direction and the substrate **2** is held in a fixed position.

[0065] Thus, in the deposition assembly **100-1**, the patterning slit sheet **130** may be much smaller than an FMM used in a comparable deposition method. In other words, in the deposition assembly **100-1**, deposition is continuously performed, i.e., in a scanning manner while the substrate **2** moves in the Y-axis direction. Thus, at least one of the lengths of the patterning slit sheet **130** in X-axis and Y-axis directions may be much less than a length of the substrate **2**. Since the patterning slit sheet **130** may be formed to be much smaller than the FMM used in a comparable deposition method, it is easy to manufacture the patterning slit sheet **130**. That is, the small patterning slit sheet **130** is more advantageous in the manufacturing processes, including etching followed by precise elongation, welding, transferring, and washing processes, than the FMM used in a comparable deposition method. In addition, this is more advantageous for manufacturing a relatively large display apparatus.

[0066] In order to perform deposition while the deposition assembly **100-1** and the substrate **2** move relative to each other as described above, the deposition assembly **100-1** and the substrate **2** may be spaced apart from each other by a certain distance. This is described below in more detail.

[0067] The deposition source **110** that contains and heats the deposition material **115** is disposed at a side opposite (facing) a side in which the substrate **2** is disposed in the chamber. As the deposition material **115** contained in the deposition source **110** is vaporized, deposition is performed on the substrate **2**.

[0068] The deposition source **110** includes a crucible **111** that is filled with the deposition material **115** and a heater **112** that heats the crucible **111** so as to vaporize the deposition

material **115** toward a side of the crucible **111** filled with the deposition material **115**, in particular, toward the deposition source nozzle unit **120**.

[0069] In one embodiment, the deposition source nozzles **121** are disposed at a side of the deposition source **110** facing the substrate **2**. In this regard, the deposition assemblies according to the present embodiment each may include different deposition nozzles in performing deposition for forming common layers and pattern layers. This structure will be described below in more detail.

[0070] FIG. **5** is a perspective view of deposition source nozzles for forming a pattern layer. FIG. **6** is a perspective view of deposition source nozzles for forming a common layer.

[0071] Referring to FIG. **5**, the deposition assembly **100-5** includes the three deposition sources **110** and three deposition source nozzle units **120**. Each deposition source nozzle unit **120** includes a deposition source nozzle **121** at a central portion thereof. The deposition material **115** that has been vaporized in the deposition source **110** passes through the deposition source nozzle unit **120** and is deposited onto the substrate **2** on which the deposition material **115** is to be deposited. The deposition source nozzle **121** is formed in the deposition source nozzle unit **120**, and the three deposition sources **110** are arranged in the deposition assembly **100-5** along a scanning direction of the substrate **2**. That is, a plurality of deposition source nozzles **121** may be formed in the deposition assembly **100-5** along the scanning direction of the substrate **2** (i.e., the direction the substrate **2** is moving). If the plurality of deposition source nozzles **121** are arranged in the X-axis direction (i.e., the direction perpendicular to the direction the substrate **2** is moving), distances between the respective deposition source nozzles **121** and a patterning slit **131** (see FIG. **16**) are different from each other, and thus, a shadow occurs on the substrate **2** due to the deposition material **115** discharged from the deposition source nozzles **121** that are disposed far from the patterning slit **131**. Thus, in the present embodiment, the deposition source nozzles **121** are formed such that only one line of the deposition source nozzles **121** is formed in the Y-axis direction in order to significantly reduce the occurrence of shadows. In addition, the deposition source nozzles **121** are arranged in the scanning direction of the substrate **2**, and thus, a flux difference between the deposition source nozzles **121** may be compensated for and deposition uniformity may be maintained constant.

[0072] Although not illustrated in FIGS. **5** and **6**, two of the three deposition sources **110**, that is, the lateral depositions sources, may be used to deposit a host material, and the central deposition source **110** may be used to deposit a dopant material. As described above, the deposition apparatus according to the present embodiment includes both a deposition source for depositing a host material and a deposition source for depositing a dopant material, and thus, the host material and the dopant material may be co-deposited on the substrate **2**. Thus, the manufacturing processes may be simplified and performed fast, and thus, a manufacturing yield of an organic light-emitting display apparatus may increase.

[0073] Referring to FIG. **6**, a deposition source nozzle unit **120'** is disposed at a side of the deposition source **110'**, and in particular, at the side of the deposition source **110'** facing the substrate **2**. The deposition source nozzle unit **120'** includes a plurality of deposition source nozzles **121'** arranged along an X-axis direction (i.e., a direction perpendicular to the scan-

ning direction of the substrate **2**). In this regard, the plurality of deposition source nozzles **121'** may be arranged at equal intervals or at smaller intervals towards both ends thereof. A deposition material that has been vaporized in the deposition source **110'** passes through the deposition source nozzles **121'** of the deposition source nozzle unit **120'** and is then deposited onto the substrate **2**. By arranging the plurality of deposition source nozzles **121'** along the X-axis direction (i.e., a direction perpendicular to the scanning direction of the substrate **2**) so as to form a common layer, a thickness uniformity of the common layer may be improved.

[0074] In one embodiment, the patterning slit sheet **130** may be disposed between the deposition source **110** and the substrate **2**. The patterning slit sheet **130** (see FIG. **16**) may further include a frame **135** having a shape similar to a window frame. The patterning slit sheet **130** includes a plurality of patterning slits **131** arranged in the X-axis direction. The deposition material **115** that has been vaporized in the deposition source **110** passes through the deposition source nozzle unit **120** and the patterning slit sheet **130** and is then deposited onto the substrate **2**. In this regard, the patterning slit sheet **130** may be formed using the same method as that used to form an FMM, in particular, a stripe-type mask, e.g., using etching. In this regard, a total number of patterning slits **131** may be higher than a total number of deposition source nozzles **121**.

[0075] In one embodiment, the deposition source **110** (and the deposition source nozzle unit **120** combined thereto) and the patterning slit sheet **130** may be spaced apart from each other by a certain distance.

[0076] As described above, deposition is performed while the deposition assembly **100-1** moves relative to the substrate **2**. In order for the deposition assembly **100-1** to move relative to the substrate **2**, the patterning slit sheet **130** is disposed spaced apart from the substrate **2** by a certain distance.

[0077] In a comparable deposition method using an FMM, deposition is performed with the FMM in close contact with the substrate in order to prevent formation of shadows on the substrate. However, in this case, defects due to the contact between the substrate and the FMM may occur. In addition, since it is difficult to move the mask with respect to the substrate, the mask and the substrate need to be formed to have the same size. Accordingly, the mask needs to be large as the size of a display apparatus increases. However, it is difficult to form a large mask.

[0078] To address these problems, in the deposition assembly **100-1** according to the present embodiment, the patterning slit sheet **130** is formed spaced apart by a certain distance from the substrate **2** on which the deposition material is to be deposited.

[0079] According to the present embodiment, deposition may be performed while a mask that is smaller than a substrate is moved with respect to the substrate, and thus, it is easier to manufacture the mask. In addition, defects due to contact between the substrate and the mask may be prevented. In addition, since it is unnecessary to closely contact the substrate with the mask during the deposition process, the manufacturing speed may be improved.

[0080] Hereinafter, the particular disposition of each element of the upper housing **104** will be described.

[0081] Referring back to FIGS. **3** and **4**, the deposition source **110** and the deposition source nozzle unit **120** are disposed on a bottom portion of the upper housing **104**. Accommodation portions **104-1** are respectively formed on

both sides of the deposition source **110** and the deposition source nozzle unit **120** to have a protruding shape. The first stage **150**, the second stage **160**, and the patterning slit sheet **130** are sequentially formed on the accommodation portions **104-1** in this order.

[0082] In this regard, the first stage **150** is formed to move in X-axis and Y-axis directions so that the first stage **150** aligns the patterning slit sheet **130** in the X-axis and Y-axis directions. That is, the first stage **150** includes a plurality of actuators so that the first stage **150** is moved in the X-axis and Y-axis directions with respect to the upper housing **104**.

[0083] The second stage **160** is formed to move in a Z-axis direction so as to align the patterning slit sheet **130** in the Z-axis direction. That is, the second stage **160** includes a plurality of actuators and is formed to move in the Z-axis direction with respect to the first stage **150**.

[0084] The patterning slit sheet **130** is disposed on the first stage **150** and the second stage **160** so as to move in the X-axis, Y-axis, and Z-axis directions, and thus, an alignment, in particular, a real-time alignment, between the substrate **2** and the patterning slit sheet **130** may be performed.

[0085] In addition, the upper housing **104**, the first stage **150**, and the second stage **160** may guide a flow path of the deposition material **115** such that the deposition material **115** discharged through the deposition source nozzles **121** is not dispersed outside the flow path. That is, the flow path of the deposition material **115** is sealed by the upper housing **104**, the first stage **150**, and the second stage **160**, and thus, the movement of the deposition material **115** in the X-axis and Y-axis directions may be thereby concurrently or simultaneously guided.

[0086] The shielding member **140** may be disposed between the patterning slit sheet **130** and the deposition source **110**. In particular, an anode or cathode pattern is formed on an edge portion of the substrate **2** and is used as a terminal for inspecting a product or for manufacturing a product. If an organic material is applied on a region of the substrate **2**, the anode or the cathode can not sufficiently perform its function. Thus, the edge portion of the substrate **2** is formed to be a non-film-forming region on which an organic material or the like is not applied. As described above, however, in the deposition apparatus, deposition is performed in a scanning manner while the substrate **2** is moved relative to the deposition apparatus, and thus, it is not easy to prevent the organic material from being deposited on the non-film-forming region of the substrate **2**.

[0087] Therefore, to prevent the organic material from being deposited on the non-film-forming region of the substrate **2**, in the deposition apparatus, the shielding member **140** may be disposed on the edge portion of the substrate **2**. Although not particularly illustrated in FIGS. 3 and 4, the shielding member **140** may include two adjacent plates.

[0088] When the substrate **2** does not pass through the deposition assembly **100-1**, the shielding member **140** screens the deposition source **110**, and thus, the deposition material **115** discharged from the deposition source **110** does not reach the patterning slit sheet **130**. When the substrate **2** enters the deposition assembly **100-1** with the shielding member **140** screening the deposition source **110**, a front part of the shielding member **140** which screens the deposition source **110** moves along with the movement of the substrate **2**, and thus, the flow path of the deposition material **115** is opened and the deposition material **115** discharged from the deposition source **110** passes through the patterning slit sheet

130 and is deposited on the substrate **2**. Also, while the substrate **2** is passing through the deposition assembly **100-1**, a rear part of the shielding member **140** moves along with the movement of the substrate **2** to screen the deposition source **110** so that the flow path of the deposition material **115** is closed. Accordingly, the deposition material **115** discharged from the deposition source **110** does not reach the patterning slit sheet **130**.

[0089] As described above, the non-film-forming region of the substrate **2** is screened by the shielding member **140**, and thus, it may be easy to prevent the organic material from being deposited on the non-film-forming region of the substrate **2** without using a separate structure.

[0090] Hereinafter, the conveyer unit **400** that conveys the substrate **2**, on which the deposition material **115** is to be deposited, is described in more detail. Referring to FIGS. 3, 4, and 7, the conveyer unit **400** includes the first conveyer unit **410**, the second conveyer unit **420**, and the transfer unit **430**.

[0091] The first conveyer unit **410** conveys in an in-line manner the transfer unit **430**, including the carrier **431** and an electrostatic chuck **432** attached thereto, and the substrate **2** attached to the transfer unit **430** so that a deposition material may be formed on the substrate **2** by the deposition assembly **100-1**. The first conveyer unit **410** includes a coil **411**, guide members **412**, upper magnetically suspended bearings, side magnetically suspended bearings, and gap sensors.

[0092] The second conveyer unit **420** returns to the loading unit **200** the transfer unit **430** from which the substrate **2** has been separated in the unloading unit **300** after one deposition cycle is completed while the transfer unit **430** is passing through the deposition unit **100**. The second conveyer unit **420** includes a coil **421**, roller guides **422**, and a charging track **423**.

[0093] The transfer unit **430** includes the carrier **431** that is conveyed along the first conveyer unit **410** and the second conveyer unit **420** and the electrostatic chuck **432** that is combined on a surface of the carrier **431** and to which the substrate **2** is attached.

[0094] Hereinafter, each element of the conveyer unit **400** will be described in more detail.

[0095] The carrier **431** of the transfer unit **430** will now be described in more detail.

[0096] Referring to FIG. 7, the carrier **431** includes a main body part **431a**, an LMS magnet **431b**, contactless power supply (CPS) modules **431c**, a power supply unit **431d**, and guide grooves **431f**.

[0097] The main body part **431a** constitutes a base part of the carrier **431** and may be formed of a magnetic material such as iron. In this regard, due to a repulsive force between the main body part **431a** and the respective upper and side magnetically suspended bearings **413** and **414**, which are described below, the carrier **431** may be maintained spaced apart from the guide members **412** by a certain distance.

[0098] The guide grooves **431f** may be respectively formed at both sides of the main body part **431a** and each may accommodate a guide protrusion **412e** of the guide member **412**.

[0099] The LMS magnet **431b** may be formed along a center line of the main body part **431a** in a direction where the main body part **431a** proceeds. The LMS magnet **431b** and the coil **411**, which are described below in more detail, may be combined with each other to constitute a linear motor, and the carrier **431** may be conveyed in an arrow A direction by the linear motor.

[0100] The CPS modules **431c** and the power supply unit **431d** may be respectively formed on both sides of the LMS magnet **431b** in the main body part **431a**. The power supply unit **431d** includes a battery (e.g., a rechargeable battery) that provides power so that the electrostatic chuck **432** can chuck the substrate **2** and maintain the chucking state. The CPS modules **431c** are wireless charging modules that charge the power supply unit **431d**. In particular, the charging track **423** formed in the second conveyer unit **420**, which are described below, is connected to an inverter, and thus, when the carrier **431** is transferred into the second conveyer unit **420**, a magnetic field is formed between the charging track **423** and the CPS modules **431c** so as to supply power to the CPS module **431c**. The power supplied to the CPS modules **431c** is used to charge the power supply unit **431d**.

[0101] The electrostatic chuck **432** may include an electrode embedded in a main body formed of ceramic, wherein the electrode is supplied with power. The substrate **2** is attached onto a surface of the main body of the electrostatic chuck **432** as a high voltage is applied to the electrode.

[0102] Hereinafter, an operation of the transfer unit **430** is described in more detail.

[0103] The LMS magnet **431b** of the main body part **431a** and the coil **411** may be combined with each other to constitute an operation unit. In this regard, the operation unit may be a linear motor. The linear motor has a small frictional coefficient, a small position error, and a very high degree of position determination, as compared to a comparable slide guide system. As described above, the linear motor may include the coil **411** and the LMS magnet **431b**. The LMS magnet **431b** is linearly disposed on the carrier **431**, and a plurality of the coils **411** may be disposed at an inner side of the chamber **101** by a certain distance so as to face the LMS magnet **431b**. Since the LMS magnet **431b** is disposed on the carrier **431** instead of the coil **411**, the carrier **431** may operate without any power supplied thereto.

[0104] In this regard, the coil **411** may be formed in an atmosphere (ATM) box in an air atmosphere and the carrier **431** to which the LMS magnet **431b** is attached may be moved in the chamber **101** maintained in vacuum.

[0105] The deposition assembly **100-1** of the deposition apparatus according to the present embodiment may further include the interval measuring assembly **170** and the sensor for an aligning process.

[0106] In detail, the interval measuring assembly **170** may measure an interval between the substrate **2** and the patterning slit sheet **130**. In this regard, the interval measuring assembly **170** is disposed to more accurately view in the chamber **101** maintained in a vacuum during deposition. For this, the interval measuring assembly **170** may be installed in an interval measuring unit accommodation unit **171** in an atmospheric state.

[0107] FIG. 8 is a schematic plan view illustrating the interval measuring assembly **170** and the patterning slit sheet **130** of the deposition apparatus according to an embodiment of the present invention.

[0108] Referring to FIG. 8, the interval measuring assembly **170** may include a first interval measuring unit **170a**, a second interval measuring unit **170b**, and a third interval measuring unit **170c**. However, the embodiments of the present invention are not limited thereto, and the interval measuring assembly **170** may include more than three interval measuring units.

[0109] In detail, the first interval measuring unit **170a** and the second interval measuring unit **170b** are arranged along a virtual first straight line, and the third interval measuring unit **170c** may be arranged along a second virtual straight line that is parallel to the first straight line. The first and second straight lines may be parallel to a first direction A. That is, the first straight line along which the first interval measuring unit **170a** and the second interval measuring unit **170b** move may be separated away in a direction orthogonal to the second straight line, which is a path along which the third interval measuring unit **170c** moves, so that the first and second straight lines may be parallel to each other.

[0110] The first interval measuring unit **170a** and the second interval measuring unit **170b** may move along the first straight line in the first direction A or in an opposite direction thereto. Also, the third interval measuring unit **170c** may move in the first direction A along the second straight line or in the opposite direction thereto.

[0111] The first interval measuring unit **170a**, the second interval measuring unit **170b**, and the third interval measuring unit **170c** may be arranged such that virtual lines connecting locations where the first interval measuring unit **170a**, the second interval measuring unit **170b**, and the third interval measuring unit **170c** are disposed form a triangle. As illustrated in FIG. 8, a right triangle may be formed by virtual lines connecting locations where the first interval measuring unit **170a**, the second interval measuring unit **170b**, and the third interval measuring unit **170c** are disposed. That is, a line connecting the locations where the first interval measuring unit **170a** and the second interval measuring unit **170b** are located may form a first side, and a line connecting the locations where the second interval measuring unit **170b** and the third interval measuring unit **170c** are located may form a second side, and a line connecting the location where the third interval measuring unit **170c** and the first interval measuring unit **170a** are located may form a third side, wherein the first side and the second side are perpendicular to each other, and the third side is the hypotenuse of a triangle. Accordingly, a right triangle may be formed by connecting locations where the first interval measuring unit **170a**, the second interval measuring unit **170b**, and the third interval measuring unit **170c** are respectively disposed.

[0112] The virtual lines that connect locations where the first interval measuring unit **170a**, the second interval measuring unit **170b**, and the third interval measuring unit **170c** are located may form a triangle also while the first interval measuring unit **170a**, the second interval measuring unit **170b**, and the third interval measuring unit **170c** move in the first direction A or in the opposite direction thereto.

[0113] The first interval measuring unit **170a**, the second interval measuring unit **170b**, and the third interval measuring unit **170c** may move individually. According to another embodiment of the present invention, the first interval measuring unit **170a** and the third interval measuring unit **170c** may move in the same direction and at the same speed.

[0114] The interval measuring units **170a**, **170b**, and **170c** may be confocal sensors. The confocal sensors may scan an object to be measured by using laser beams that rotate at high speed by using a scanning mirror and measure a distance to the object by using fluorescent or reflected rays emitted by the laser beams. The confocal sensors may measure a distance by sensing a boundary interface between different media.

[0115] FIGS. 9 through 12 are plan views illustrating an operation of measuring an interval between the substrate **2**

and the patterning slit sheet 130, by using the interval measuring unit 170 according to an embodiment of the present invention.

[0116] FIG. 9 illustrates the substrate 2 transported in the first direction A such that a first side portion 2a of the substrate 2 is located to correspond to a non-patterning portion 130a. In this case, the first interval measuring unit 170a, the second interval measuring unit 170b, and the third interval measuring unit 170c are located above portions of the substrate 2 corresponding to a portion on the non-patterning portion 130a of the patterning slit sheet 130 so as to respectively measure the distances of the first interval measuring unit, the second interval measuring unit, and the third interval measuring unit with respect to the substrate 2 and the patterning slit sheet 130, thereby calculating intervals between the substrate 2 and the patterning slit sheet 130 at each of points where the first interval measuring unit 170a, the second interval measuring unit 170b, and the third interval measuring unit 170c are located. A distance between the substrate 2 and the patterning slit sheet 130 may be calculated by subtracting the distance between the interval measuring assembly 170 and the substrate 2 from the distance between the interval measuring assembly 170 and the patterning slit sheet 130.

[0117] While the substrate 2 moves in the first direction A, the first interval measuring unit 170a, the second interval measuring unit 170b, and the third interval measuring unit 170c may move at the same speed as the substrate 2.

[0118] When there is a difference in the distances between the substrate 2 and the patterning slit sheet 130 at each of the points where the first interval measuring unit 170a, the second interval measuring unit 170b, and the third interval measuring unit 170c are located, the patterning slit sheet 130 may be moved so that distances become equal to one another. This will be further described in more detail.

[0119] FIG. 10 illustrates the substrate 2 transported in the first direction A such that the first side portion 2a of the substrate 2 moves above the patterning unit 130b.

[0120] Referring to FIG. 10, the second interval measuring unit 170b moves along the first direction A at the same speed as the transportation speed of the substrate 2 to measure a distance to the substrate 2 and a distance to the patterning slit sheet 130, thereby calculating a distance between the substrate 2 and the patterning slit sheet 130.

[0121] In this case, the first interval measuring unit 170a and the third interval measuring unit 170c may be stationary at the non-patterning unit 130a to measure the respective distances to the substrate 2 and to the patterning slit sheet 130, thereby calculating distances between the substrate 2 and the patterning slit sheet 130 at each of the points where the first interval measuring unit 170a and the third interval measuring unit 170c are located.

[0122] When there is a difference in the distances between the substrate 2 and the patterning slit sheet 130 at each of the points where the first interval measuring unit 170a, the second interval measuring unit 170b, and the third interval measuring unit 170c are located, the patterning slit sheet 130 may be moved so that the distances become equal to one another. This will be further described in more detail.

[0123] FIG. 11 illustrates the substrate 2 transported in the first direction A such that the first side portion 2a of the substrate 2 passes a portion above the patterning unit 130b so as to be also out of a portion above the non-patterning unit 130a.

[0124] In this case, while the second interval measuring unit 170b is stationary above the non-patterning unit 130a which is adjacent to the first side portion 2a of the substrate 2 with respect to the patterning unit 130b, and the first interval measuring unit 170a and the third interval measuring unit 170c are stationary above the non-patterning unit 130a which is adjacent to a second portion 2b of the substrate 2 with respect to the patterning unit 130b, each of the first interval measuring unit 170a and the third interval measuring unit 170c respectively measure distances to the substrate 2 and to the patterning slit sheet 130 to calculate distances between the substrate 2 and the patterning slit sheet 130 at their locations respectively. As described above, that is, an interval between the substrate 2 and the patterning slit sheet 130 may be calculated by subtracting the distance between the interval measuring assembly 170 and the substrate 2 from the distance between the interval measuring assembly 170 and the patterning slit sheet 130.

[0125] When there is a difference in the distances between the substrate 2 and the patterning slit sheet 130 at each of the points where the first interval measuring unit 170a, the second interval measuring unit 170b, and the third interval measuring unit 170c are located, the patterning slit sheet 130 may be moved so that the distances become equal to one another.

[0126] In detail, FIGS. 13 and 14 illustrate an arrangement of the substrate 2 and the patterning slit sheet 130. FIG. 13 illustrates a state before the substrate 2 and the patterning slit sheet 130 are aligned with respect to each other, and FIG. 14 illustrates a state after the substrate 2 and the patterning slit sheet 130 are aligned with respect to each other. Referring to FIG. 13, when the substrate 2 is moved to be disposed above the patterning slit sheet 130, the first interval measuring unit 170a, the second interval measuring unit 170b, and the third interval measuring unit 170c each measures the distances to the substrate 2 and the patterning slit sheet 130 so as to measure intervals h1, h2, and h3 between the substrate 2 and the patterning slit sheet 130 with respect to respective measuring points. As illustrated in FIG. 13, the intervals h1, h2, and h3 between the substrate 2 and the patterning slit sheet 130 may be different from one another. In this case, the first stage 150 and the second stage 160 may move the patterning slit sheet 130 in X, Y, and Z directions so that, as illustrated in FIG. 14, intervals h1', h2', and h3' between the substrate 2 and the patterning slit sheet 130 may be maintained uniformly.

[0127] FIG. 12 illustrates a case where the substrate 2 transported in the first direction A so that a portion of the patterning slit sheet 130 is not covered by the substrate 2.

[0128] In this case, the second interval measuring unit 170b is stationary above the non-patterning unit 130a which is adjacent to the first side portion 2a of the substrate 2 with respect to the patterning unit 130b, and the first interval measuring unit 170a and the third interval measuring unit 170c move along the first direction A at the same speed as a transportation speed of the substrate 2 and each of them may respectively measure their distances from the substrate 2 and from the patterning slit sheet 130 so as to measure an interval between the substrate 2 and the patterning slit sheet 130.

[0129] When there is a difference in the distances between the substrate 2 and the patterning slit sheet 130 at each of the points where the first interval measuring unit 170a, the second interval measuring unit 170b, and the third interval measuring unit 170c are located, the patterning slit sheet 130 may be moved so that the distances become equal to one another.

[0130] Since a distance between the substrate 2 and the patterning slit sheet 130 is measurable in real time by using the interval measuring assembly 170, the substrate 2 may be aligned with the patterning slit sheet 130 in real time, whereby the position accuracy of a pattern may be significantly improved.

[0131] Then, when the substrate 2 moves along the first direction A so as to be not located on the patterning slit sheet 130 anymore, the first interval measuring unit 170a, the second interval measuring unit 170b, and the third interval measuring unit 170c may move in an opposite direction to the first direction A so that, as illustrated in FIG. 8, the first interval measuring unit 170a is not located on the patterning slit sheet 130, and the second interval measuring unit 170b and the third interval measuring unit 170c may be located on the non-patterning unit 130a.

[0132] FIG. 15 is a schematic perspective view illustrating a deposition assembly 900 according to another embodiment of the present invention.

[0133] Referring to FIG. 15, the deposition assembly 900 includes a deposition source 910, a deposition source nozzle unit 920, and a patterning slit sheet 950.

[0134] The deposition source 910 includes a crucible 911 in which a deposition material 915 is filled, and a heater 912 that heats the crucible 911 to evaporate the deposition material 915 filled in the crucible 911. Meanwhile, the deposition source nozzle unit 920 is disposed on a side portion of the deposition source 910, and the deposition source nozzle unit 920 includes a plurality of deposition nozzles 921 that are arranged along the Y-axis direction. Meanwhile, a patterning slit sheet 950 and a frame 955 are further disposed between the deposition source 910 and the substrate 500, and a plurality of patterning slits 951 are formed in the patterning slit sheet 950 along a X-axis direction. In addition, the deposition source 910, the deposition nozzle unit 920, and the patterning slit sheet 950 are coupled to one another by using a connection member 935.

[0135] The current embodiment of the present invention is different from above-described embodiments in regard to the arrangement of the plurality of deposition source nozzles 921 included in the deposition source nozzle unit 920. This will be described in more detail.

[0136] The deposition source nozzle unit 920 is disposed on a side of the deposition source 910, that is, on a side in a direction from the deposition source 910 towards the substrate 500. A plurality of deposition source nozzles 921 are formed in the deposition source nozzle unit 920 in the Y-direction, that is, along a scanning direction of the substrate 500. Here, the plurality of deposition source nozzles 921 may be arranged at equal intervals. The deposition material 915 that is gasified in the deposition source 910 passes through the deposition source nozzle unit 920 towards the substrate 500 which is a substrate material to be deposited on. As a result, a plurality of deposition nozzles 921 are formed in a single deposition assembly 900-1 along the scanning direction. In another case, if a plurality of deposition source nozzles 921 are included in the X-axis direction, distances between the respective deposition source nozzles 921 and the patterning slits 951 are various, and a shadow may form by a deposition material that is emitted from those deposition source nozzles 921 that are relatively far from the patterning slits 951. Accordingly, by forming the deposition source nozzles 951 such that only one deposition source nozzle 921 is disposed in the X-axis direction as in the current embodiment of the

present invention, formation of a shadow may be significantly reduced. Also, as a plurality of deposition source nozzles 921 are present in the scanning direction, even if a flux difference exists between the individual deposition source nozzles 921, the flux difference may be offset so that deposition uniformity may be maintained.

[0137] Hereinafter, a structure of an organic layer formed using the deposition apparatus described above is described in more detail.

[0138] FIG. 16 is a diagram illustrating a structure in which the patterning slits 131 are arranged at equal intervals in the patterning slit sheet 130 of the deposition apparatus including the deposition unit 100 of FIG. 2, according to an embodiment of the present invention. FIG. 17 is a diagram illustrating organic layers formed on the substrate by using the patterning slit sheet 130 of FIG. 16, according to an embodiment of the present invention.

[0139] FIGS. 16 and 17 illustrate the patterning slit sheet 130 in which the patterning slits 131 are arranged at equal intervals. That is, in FIG. 16, the patterning slits 131 satisfy the following condition: $I_1=I_2=I_3=I_4$.

[0140] In this embodiment, an incident angle of a deposition material discharged along a center line C of a deposition space S is substantially a right angle with respect to the substrate. Thus, a deposition layer P₁ formed using the deposition material that has passed through a patterning slit 131a has a shadow with a reduced or minimum size, and a right-side shadow SR₁ and a left-side shadow SL₁ are formed symmetrical to each other.

[0141] However, a critical incident angle θ of the deposition material that passes through patterning slits disposed farther from the center line C of the deposition space S gradually increases, and thus, the critical incident angle θ of the deposition material that passes through the outermost patterning slit 131e is approximately 55°. Accordingly, the deposition material is incident at an inclination with respect to the patterning slit 131e, and a deposition layer P₅ formed using the deposition material that has passed through the patterning slit 131e has the largest shadow. In particular, a left-side shadow SR₅ is larger than a right-side shadow SR₅.

[0142] That is, as the critical incident angle θ of the deposition material increases, the size of the shadow also increases. In particular, the size of the shadow at a position farther from the center line C of the deposition space S increases. In addition, the critical incident angle θ of the deposition material increases as a distance between the center line C of the deposition space S and the respective patterning slits increases. Thus, deposition layers formed using the deposition material that passes through the patterning slits disposed farther from the center line C of the deposition space S have a larger shadow size. In particular, of the shadows on both sides of the respective deposition layers, the size of the shadow at a position farther from the center line C of the deposition space S is larger than that of the other.

[0143] That is, referring to FIG. 17, the deposition layers formed on the left side of the center line C of the deposition space S have a right angle triangular shadow structure on each side of a deposited layer in which a left hypotenuse is larger than a right hypotenuse, and the deposition layers formed on the right side of the center line C of the deposition space S have a structure in which a right hypotenuse is larger than a left hypotenuse.

[0144] Also, in the deposition layers formed on the left side of the center line C of the deposition space S, the length of the

left hypotenuse increases towards the left. In the deposition layers formed on the right side of the center line C of the deposition space S, the length of the right hypotenuse increases towards the right. Consequently, the deposition layers formed in the deposition space S may be formed symmetrical to each other with respect to the center line C of the deposition space S.

[0145] This structure will now be described in more detail.

[0146] The deposition material that passes through a patterning slit 131b passes through the patterning slit 131b at a critical incident angle θ_b , and a deposition layer P₂ formed using the deposition material that has passed through the patterning slit 131b has a left-side shadow having a size SL₂. Similarly, the deposition material that passes through a patterning slit 131c passes through the patterning slit 131c at a critical incident angle θ_c , and a deposition layer P₃ formed using the deposition material that has passed through the patterning slit 131c has a left-side shadow having a size SL₃. Similarly, the deposition material that passes through a patterning slit 131d passes through the patterning slit 131d at a critical incident angle θ_d , and a deposition layer P₄ formed using the deposition material that has passed through the patterning slit 131d has a left-side shadow having a size SL₄. Similarly, the deposition material that passes through the patterning slit 131e passes through the patterning slit 131e at a critical incident angle θ_e , and a deposition layer P₅ formed using the deposition material that has passed through the patterning slit 131e has a left-side shadow having a size SL₅.

[0147] In this regard, the critical incident angles satisfy the following inequality $\theta_b < \theta_c < \theta_d < \theta_e$, and thus, the sizes of the shadows of the deposition layers also satisfy the following inequality $SL_1 < SL_2 < SL_3 < SL_4 < SL_5$.

[0148] FIG. 18 is a cross-sectional view of an active matrix-type organic light-emitting display apparatus manufactured using the deposition apparatus, according to an embodiment of the present invention.

[0149] Referring to FIG. 18, the active matrix organic light-emitting display apparatus according to the current embodiment is formed on the substrate 50. The substrate 50 may be formed of a transparent material, for example, glass, plastic, or metal. An insulating layer 51, such as a buffer layer, is formed on an entire surface of the substrate 50.

[0150] A thin film transistor (TFT), a capacitor, and an organic light-emitting diode (OLED) are disposed on the insulating layer 51, as illustrated in FIG. 17.

[0151] A semiconductor active layer 52 is formed on an upper surface of the insulating layer 51 in a set or predetermined pattern. A gate insulating layer 53 is formed to cover the semiconductor active layer 52. The semiconductor active layer 52 may include a p-type or n-type semiconductor material.

[0152] A gate electrode 54 of the TFT is formed in a region of the gate insulating layer 53 corresponding to the semiconductor active layer 52. An interlayer insulating layer 55 is formed to cover the gate electrode 54. The interlayer insulating layer 53 and the gate insulating layer 53 are etched by, for example, dry etching, to form a contact hole exposing parts of the semiconductor active layer 52.

[0153] Source/drain electrodes 56 and 57 are formed on the interlayer insulating layer 55 to contact the semiconductor active layer 52 through the contact hole. A passivation layer 58 is formed to cover the source/drain electrodes 56 and 57, and is etched to expose a part of one of the source/drain

electrodes 56 and 57. An insulating layer 59 may be further formed on the passivation layer 58 so as to planarize the passivation layer 58.

[0154] In addition, the OLED displays set or predetermined image information by emitting red, green, or blue light according to an applied current. The OLED includes a first electrode 61 disposed on the passivation layer 58. The first electrode 61 is electrically connected to the exposed source/drain electrode 57 of the TFT.

[0155] A pixel-defining layer 60 is formed to cover the first electrode 61. An opening is formed in the pixel-defining layer 60, and a deposition layer 62 including an emission layer (EML) is formed in a region defined by the opening. A second electrode 63 is formed on the deposition layer 62.

[0156] The pixel-defining layer 60, which defines individual pixels, is formed of an organic material. The pixel-defining layer 60 also planarizes the surface of a region of the substrate in which the first electrode 61 is formed, and in particular, the surface of the insulating layer 59.

[0157] The first electrode 61 and the second electrode 62 are insulated from each other, and respectively apply voltages of opposite polarities to the organic layer 63 to induce light emission.

[0158] The organic layer 63, including an EML, may be formed of a low-molecular weight organic material or a high-molecular weight organic material. When a low-molecular weight organic material is used, the organic layer 63 may have a single or multi-layer structure including a hole injection layer (HIL), a hole transport layer (HTL), the EML, an electron transport layer (ETL), and/or an electron injection layer (EIL). Non-limiting examples of suitable organic materials may include copper phthalocyanine (CuPc), N,N'-di(naphthalene-1-yl)-N,N'-diphenyl-benzidine (NPB), and tris-8-hydroxyquinoline aluminum (Alq₃).

[0159] The organic layer 63 including an EML may be formed using the deposition apparatus illustrated in FIGS. 1 through 10. That is, a deposition apparatus, which includes a deposition source that discharges a deposition material, a deposition source nozzle unit that is disposed at a side of the deposition source and includes a plurality of deposition source nozzles formed therein, and a patterning slit sheet that faces the deposition source nozzle unit and includes a plurality of patterning slits formed therein, is disposed spaced apart by a set or predetermined distance from a substrate on which the deposition material is to be deposited. In addition, the deposition material discharged from the deposition apparatus is deposited on the substrate 2 while the deposition apparatus and the substrate 2 are moved relative to each other.

[0160] After the organic layer 63 is formed, the second electrode 62 may be formed by the same deposition method as the organic layer 63.

[0161] The first electrode 61 may function as an anode, and the second electrode 62 may function as a cathode. Alternatively, the first electrode 61 may function as a cathode, and the second electrode 62 may function as an anode. The first electrode 61 may be patterned to correspond to individual pixel regions, and the second electrode 62 may be formed to cover all the pixels.

[0162] The first electrode 61 may be formed as a transparent electrode or a reflective electrode. Such a transparent electrode may be formed of indium tin oxide (ITO), indium zinc oxide (IZO), zinc oxide (ZnO), or indium oxide (In₂O₃). Such a reflective electrode may be formed by forming a reflective layer from silver (Ag), magnesium (Mg), aluminum

(Al), platinum (Pt), palladium (Pd), gold (Au), nickel (Ni), neodymium (Nd), indium (Ir), chromium (Cr) or a compound thereof and forming a layer of ITO, IZO, ZnO, or In_2O_3 on the reflective layer. The first electrode **61** may be formed by forming a layer by, for example, sputtering, and then patterning the layer by, for example, photolithography.

[0163] The second electrode **62** may also be a transparent electrode or a reflective electrode. When the second electrode **62** is a transparent electrode, the second electrode **62** is used as a cathode. To this end, such a transparent electrode may be formed by depositing a metal having a low work function, such as lithium (Li), calcium (Ca), lithium fluoride/calcium (LiF/Ca), lithium fluoride/aluminum (LiF/Al), aluminum (Al), silver (Ag), magnesium (Mg), or a compound thereof on a surface of the organic layer **63** and forming an auxiliary electrode layer or a bus electrode line thereon from ITO, IZO, ZnO, In_2O_3 , or the like. When the second electrode **62** is a reflective electrode, the reflective layer may be formed by depositing Li, Ca, LiF/Ca, LiF/Al, Al, Ag, Mg, or a compound thereof on the entire surface of the organic layer **63**. The second electrode **62** may be formed using the same deposition method as the organic layer **63** described above.

[0164] The deposition apparatuses according to the embodiments of the present invention described above may be used to form an organic layer or an inorganic layer of an organic TFT and other layers from various materials.

[0165] As described above, the one or more embodiments of the present invention provide deposition apparatuses that are suitable for use in mass producing large substrates and enable high-definition patterning, methods of manufacturing organic light-emitting display apparatuses by using the same, and organic light-emitting display apparatuses manufactured using the methods.

[0166] Although a few embodiments of the present invention have been shown and described, it would be appreciated by those skilled in the art that changes may be made in these embodiments without departing from the principles and spirit of the invention, the scope of which is defined in the claims and their equivalents.

What is claimed is:

1. A method of manufacturing an organic light emitting display apparatus, the method comprising:

fixing a substrate to a transfer unit at a loading unit;
transporting the transfer unit on which the substrate is fixed in a first direction into a chamber by using a first conveyer unit that passes through the chamber;
depositing a deposition material that is emitted from a deposition assembly by moving one of the substrate or the deposition assembly relative to the other, while the deposition assembly arranged in the chamber and the substrate are separated from each other by a distance;
separating the substrate on which deposition is completed from the transfer unit at an unloading unit; and
transporting the transfer unit that is separated from the substrate to the loading unit by using a second conveyer unit,

wherein the depositing of the deposition material comprises measuring an interval between the substrate and the deposition assembly while the one of the substrate or the deposition assembly moves relative to the other.

2. The method of claim 1, wherein additional deposition assemblies are arranged in the chamber so as to perform deposition on the substrate consecutively.

3. The method of claim 1, wherein the transfer unit is circulated by the first conveyer unit and the second conveyer unit.

4. The method of claim 1, wherein one of the first conveyer unit and the second conveyer unit is arranged on top of the other.

5. The method of claim 1, wherein a patterning slit sheet of the deposition assembly is smaller than the substrate in at least one of the first direction or a second direction perpendicular to the first direction.

6. The method of claim 1, wherein the deposition assembly comprises:

a deposition source configured to discharge the deposition material;

a deposition source nozzle unit installed at a side of the deposition source and comprising a plurality of deposition source nozzles;

a patterning slit sheet facing the deposition source nozzle unit and comprising a plurality of patterning slits formed along a direction; and

an interval measuring assembly configured to move relative to the substrate and the patterning slit sheet in order to measure an interval between the substrate and the patterning slit sheet,

wherein the patterning slit sheet comprises a patterning unit having a plurality of patterning slits and a non-patterning unit that surrounds the patterning unit and does not have a patterning slit, and

wherein the interval measuring assembly comprises at least three interval measuring units, and the at least three interval measuring units are located on a single virtual plane, and are not arranged along a straight line.

7. The method of claim 6, wherein the at least three interval measuring units comprise a first interval measuring unit, a second interval measuring unit, and a third interval measuring unit,

wherein virtual lines that connect the first interval measuring unit, the second interval measuring unit, and the third interval measuring unit form a triangle, and

while the first interval measuring unit, the second interval measuring unit, and the third interval measuring unit move in a first direction or in a third direction opposite the first direction, the virtual lines that connect the first interval measuring unit, the second interval measuring unit, and the third interval measuring unit form a triangle.

8. The method of claim 7, wherein the measuring of the interval comprises, when the substrate is transported in the first direction such that a side portion of the substrate is located on the non-patterning unit:

measuring a distance with respect to the substrate and a distance with respect to the patterning slit sheet while the first interval measuring unit, the second interval measuring unit, and the third interval measuring unit are located above a portion of the substrate corresponding to the non-patterning unit, so as to calculate intervals between the substrate and the patterning slit sheet at each of the locations where the first interval measuring unit, the second interval measuring unit, and the third interval measuring unit are located; and

when there is a difference in the intervals between the patterning slit sheet and the substrate at each of the positions where the first interval measuring unit, the second interval measuring unit, and the third interval

measuring unit are located, moving the patterning slit sheet such that the intervals become identical.

9. The method of claim 7, wherein the measuring of an interval comprises,

when the substrate is transported in the first direction so that a side portion of the substrate passes above the patterning unit;

calculating an interval between the substrate and the patterning slit sheet by using the second interval measuring unit moving at a same speed as a transportation speed of the substrate in the first direction to measure distances of the second interval measuring unit with respect to the substrate and the patterning slit sheet; and

when there is a difference in intervals between the substrate and the patterning slit sheet at each of the positions where the first interval measuring unit, the second interval measuring unit, and the third interval measuring unit are located, moving the patterning slit sheet such that the intervals become identical.

10. The method of claim 9, wherein the first interval measuring unit and the third interval measuring unit are stationary above the non-patterning unit to measure respective distances of the first interval measuring unit and the third interval measuring unit with respect to the substrate and the patterning slit sheet to calculate intervals between the substrate and the patterning slit sheet.

11. The method of claim 7, wherein the measuring of the interval comprises, when the substrate is transported in the first direction so that a first side portion of the substrate passes above the patterning unit and the non-patterning unit to be out of the non-patterning unit:

calculating intervals between the substrate and the patterning slit sheet by measuring respective distances of the first, second, and third interval measuring units with respect to the substrate and the patterning slit sheet, the second interval unit being stationary above a portion of the non-patterning unit adjacent to a first side portion of the substrate with respect to the patterning unit, and the first interval measuring unit and the third interval measuring unit being stationary above portions of the non-patterning unit adjacent to a second side portion of the substrate opposite to the first side portion with respect to the patterning unit; and

when there is a difference in intervals between the substrate and the patterning slit sheet at each of the portions where the first interval measuring unit, the second interval measuring unit, and the third interval measuring unit are located, moving the patterning slit sheet such that the intervals become identical.

12. The method of claim 7, wherein the measuring of the interval comprises, when the substrate is transported in the first direction so that a portion of the patterning slit sheet does not correspond to the substrate:

calculating intervals between the substrate and the patterning slit sheet by measuring respective distances of the first, second, and third interval measuring units with respect to the substrate and the patterning slit sheet, the second interval unit being stationary above a portion of the non-patterning unit adjacent to a first side portion of the substrate with respect to the patterning unit, and the first interval measuring unit and the third interval measuring unit moving in the first direction at a same speed as a transportation speed of the substrate; and

when there is a difference in intervals between the substrate and the patterning slit sheet at each of the portions where the first interval measuring unit, the second interval measuring unit, and the third interval measuring unit are located, moving the patterning slit sheet such that the intervals become identical.

13. The method of claim 6, wherein the plurality of deposition source nozzles forms one line along the first direction.

14. The method of claim 6, wherein the plurality of deposition source nozzles are spaced apart along a second direction perpendicular to the first direction.

15. An organic light-emitting display apparatus comprising:

a substrate;

a thin film transistor on the substrate and comprising a semiconductor active layer, a gate electrode insulated from the semiconductor active layer, and source and drain electrodes each contacting the semiconductor active layer;

a plurality of pixel electrodes on the thin film transistor;

a plurality of deposition layers on the plurality of the pixel electrodes; and

a counter electrode on the plurality of deposition layers,

wherein a length of a hypotenuse of at least one of the plurality of deposition layers on the substrate farther from a center of a deposition region is greater than lengths of hypotenuses of other deposition layers formed closer to the center of the deposition region, and

wherein the at least one of the plurality of deposition layers on the substrate is a linearly-patterned deposition layer formed by using the method of claim 1.

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专利名称(译)	制造有机发光显示装置的方法，以及通过该方法制造的有机发光显示装置		
公开(公告)号	US20140284561A1	公开(公告)日	2014-09-25
申请号	US13/946945	申请日	2013-07-19
[标]申请(专利权)人(译)	三星显示有限公司		
申请(专利权)人(译)	三星DISPLAY CO. , LTD.		
当前申请(专利权)人(译)	三星DISPLAY CO. , LTD.		
[标]发明人	CHANG YUN HO YOON MI JOO		
发明人	CHANG, YUN-HO YOON, MI-JOO		
IPC分类号	H01L51/00 H01L27/32		
CPC分类号	H01L27/3248 H01L51/0012 H01L27/3244 H01L51/0011		
优先权	1020130029910 2013-03-20 KR		
其他公开文献	US9136476		
外部链接	Espacenet USPTO		

摘要(译)

一种制造有机发光显示装置的方法，以及通过该方法制造的有机发光显示装置，该方法适合于大规模生产大型基板，能够实现高清晰度图案化，并且允许控制图案化缝隙之间的距离片材和基材相对于彼此移动。

